

F7030 Rentgenový rozptyl na tenkých vrstvách

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PřF MU

Prezentace k přednášce
Numerické simulace
Příklady experimentů
Vybrané vztahy

Syllabus

1. Experimentální technika: zdroje, vznik rtg záření, goniometry, optické prvky (monochromátory, kolimátory, zrcadla, fokusační optika), detektory. Základní experimenty: polykrystalové a monokrystalové metody, mapování reciprokého prostoru
2. Kinematická teorie rozptylu: úvod do teorie rozptylu, rozptyl na elektronu, izolovaném atomu, krystal, strukturní a geometrický faktor, omezená velikost krystalu
3. Difrakce na polykrystalech I: strukturní faktor, velikost krystalitu (Scherrerova formule), vliv deformace na polohy a šířky difrakčních maxim, zbytková napětí, kvantifikace fázového složení (vnitřní normál)
4. Polykrystaly II: Full profile fitting; Texture, ODF (orientation distribution function); Debyeův vztah, PDF (pair distribution function).
5. SAXS: teoretický popis, řídké roztoky – Guinierův a Porodův vztah, uspořádané částice – long range a short-range order
6. Dokonalé, téměř dokonalé krystaly, epitaxní vrstvy: Kinematická teorie na monokrystalu a epitaxní vrstvě – polohy difrakcí, truncation rod, deformace v epitaxní vrstvě, relaxace. Mozaikový krystal
7. Dynamická teorie rtg reflexe: Jednovlnná aproximace – hloubka vniku, reflexe na hladkém rozhraní, multivrstvy (formalismus přenosové matice), TRXRF
8. Dynamická teorie rtg difrakce: Dvojevlnná aproximace: případ Bragg a Laue, Borrmannův jev, stojatá vlna, GID, epitaxní vrstvy
9. Semikinematická teorie I: DWBA, Rozptyl na drsných rozhraních – popis drsného rozhraní, příklady: fraktálové rozhraní, dvouúrovňové, vicinální, spekulární odraz a nespekulární rozptyl, drsné multivrstvy
10. Semikinematická teorie II: GISAXS na částicích na povrchu a uvnitř vzorku, Difuzní rozptyl na defektech v krystalu v okolí difrakce
11. Experimentální rozlišení Experimentální rozlišení v reciprokém prostoru: analyzer streak, detector streak, monochromator streak, DuMondovy grafy, disperzní a nedisperzní uspořádání, koherenční šířka a délka
12. Další rentgenové metody: Fluorescenční spektroskopie, absorpční spektroskopie – XAFS, XMCD.

Velký monokrystal

$$F^{crystal}(\mathbf{Q}) = \sum_{\ell}^{\text{All atoms}} f_{\ell}(\mathbf{Q}) e^{i\mathbf{Q} \cdot \mathbf{r}_{\ell}}$$

$$F^{crystal}(\mathbf{Q}) = \sum_{\mathbf{R}_n + \mathbf{r}_j}^{\text{All atoms}} f_j(\mathbf{Q}) e^{i\mathbf{Q} \cdot (\mathbf{R}_n + \mathbf{r}_j)} = \underbrace{\sum_n e^{i\mathbf{Q} \cdot \mathbf{R}_n}}_{\text{Lattice}} \underbrace{\sum_j f_j(\mathbf{Q}) e^{i\mathbf{Q} \cdot \mathbf{r}_j}}_{\text{Unit cell}}$$

$$F^{u.c.}(\mathbf{Q}) = \sum_j f_j(\mathbf{Q}) e^{i\mathbf{Q} \cdot \mathbf{r}_j}$$

One dimension

$$S_N(\mathbf{Q}) = \sum_{n=0}^{N-1} e^{i\mathbf{Q}na}$$

$$|S_N(\mathbf{Q})| = \frac{\sin(N\mathbf{Q}a/2)}{\sin(\mathbf{Q}a/2)}$$

$$\mathbf{Q} = (h + \xi)\mathbf{a}^* \quad |S_N(\xi)| = \frac{\sin(N\pi\xi)}{\sin(\pi\xi)} \rightarrow N \text{ as } \xi \rightarrow 0$$

Its width for large N may be estimated by setting $\xi = 1/(2N)$:

$$|S_N(\xi = \frac{1}{2N})| \approx \frac{1}{\pi/(2N)} = \left(\frac{2}{\pi}\right) N \approx \frac{N}{2}$$

$$N \rightarrow \infty$$

$$|S_N(\xi)| \rightarrow \delta(\xi)$$

$$|S_N(\mathbf{Q})| \rightarrow a^* \sum_{\mathbf{G}_h} \delta(\mathbf{Q} - \mathbf{G}_h)$$

$$|S_N(\mathbf{Q})|^2 \rightarrow N a^* \sum_{\mathbf{G}_h} \delta(\mathbf{Q} - \mathbf{G}_h)$$

Velký monokrystal

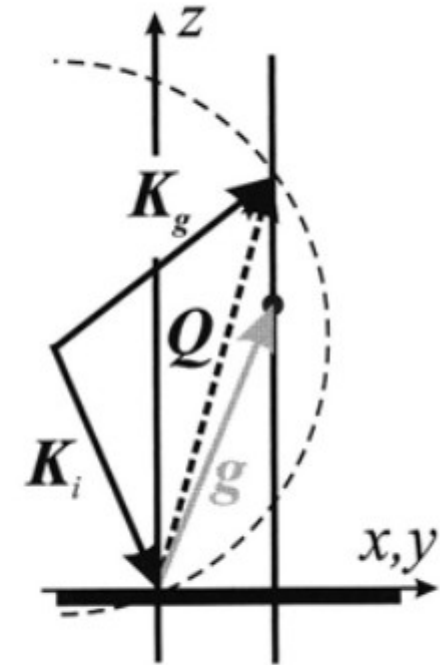
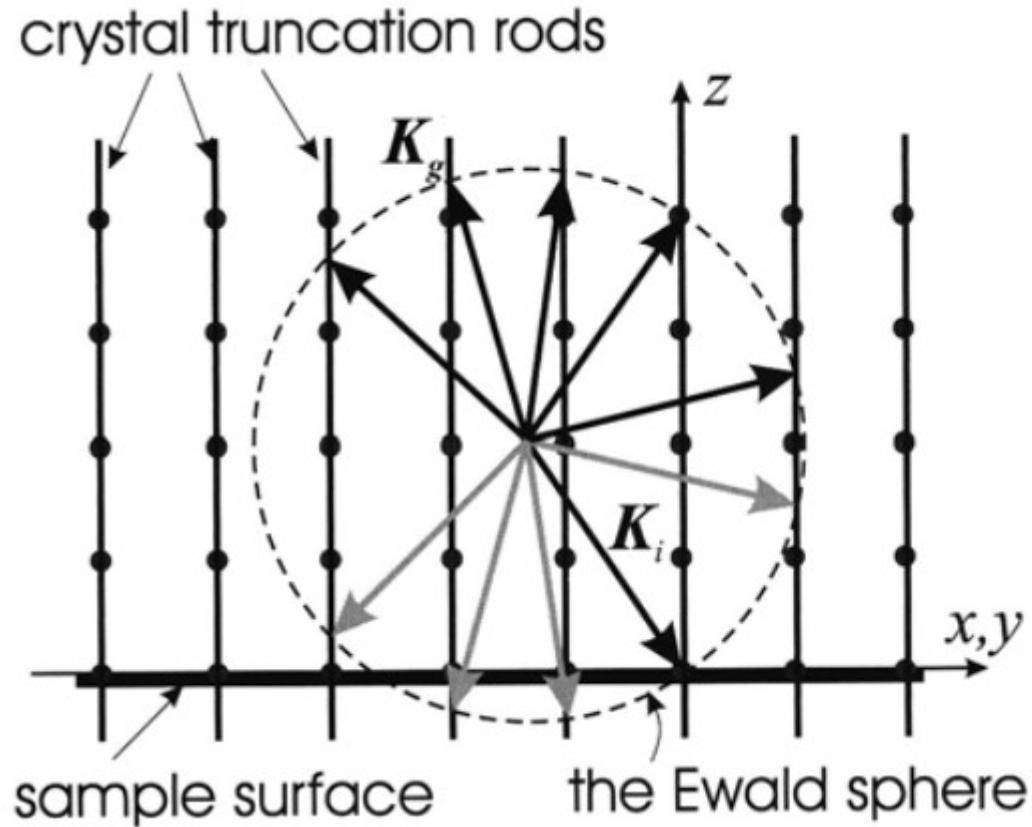
Two and three dimensions

$$|S_N(\xi_1, \xi_2)|^2 \rightarrow N_1 N_2 \delta(\xi_1) \delta(\xi_2)$$

$$|S_N(\mathbf{Q})|^2 \rightarrow (N_1 a_1^*)(N_2 a_2^*) \sum_{\mathbf{G}} \delta(\mathbf{Q} - \mathbf{G}) = NA^* \sum_{\mathbf{G}} \delta(\mathbf{Q} - \mathbf{G})$$

$$|S_N(\mathbf{Q})|^2 \rightarrow N v_c^* \sum_{\mathbf{G}} \delta(\mathbf{Q} - \mathbf{G})$$

Velký monokrystal



Velký monokrystal

$$F^{\text{CTR}} = A(\mathbf{Q}) \sum_{j=0}^{\infty} e^{iQ_z a_3 j} e^{-\beta j} = \frac{A(\mathbf{Q})}{1 - e^{iQ_z a_3} e^{-\beta}}$$

$A(\mathbf{Q})$ is the scattering amplitude from a layer of atoms

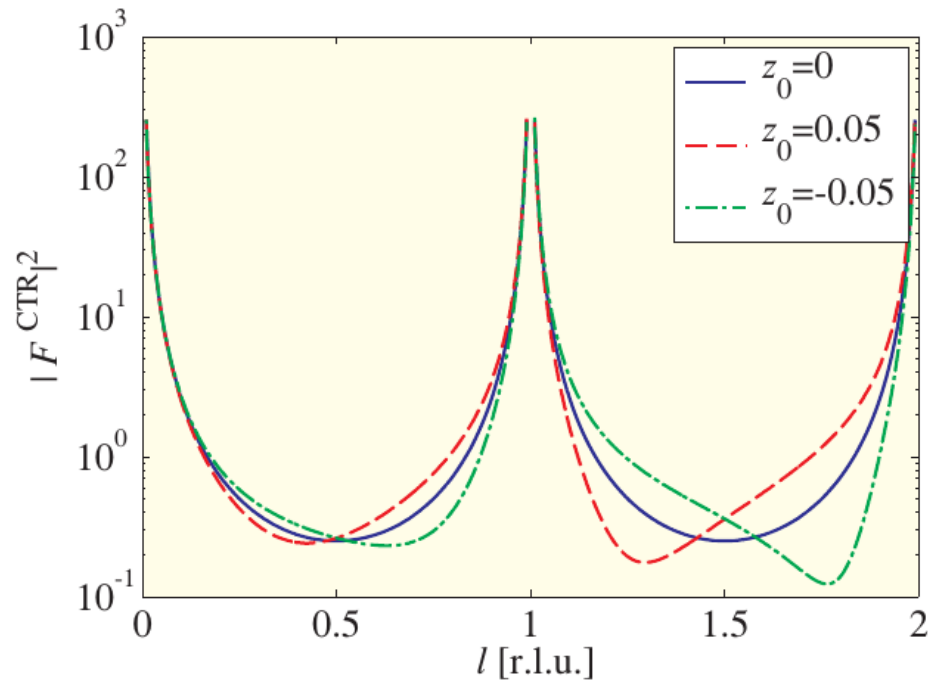
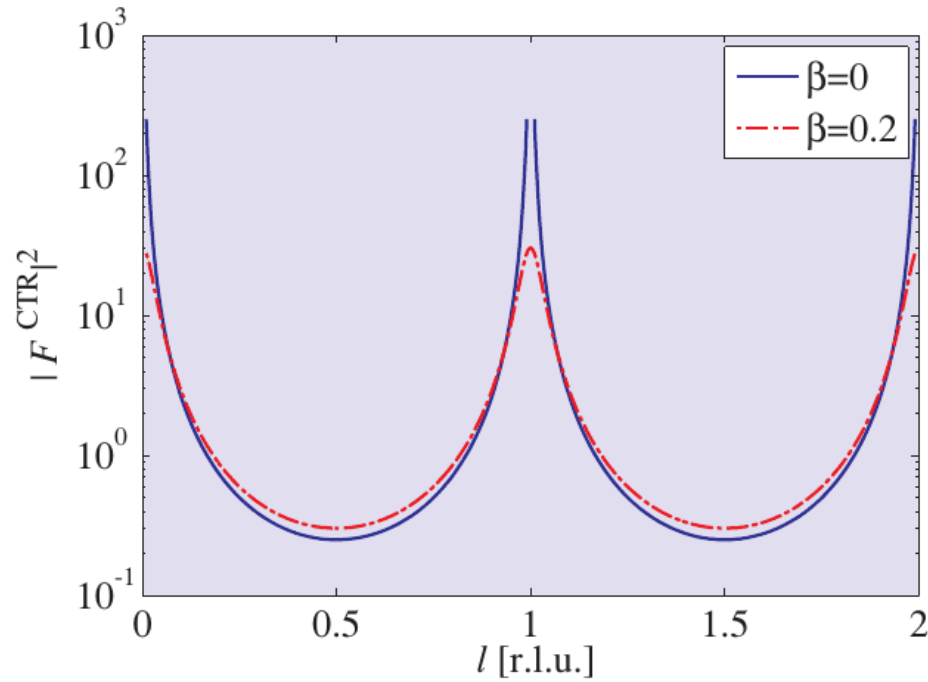
$$\delta(Q_x - ha_1^*) \delta(Q_y - ka_2^*)$$

$\beta = a_3 \mu / \sin \theta$ is the absorption parameter per layer.

$$I^{\text{CTR}} = |F^{\text{CTR}}|^2 = \frac{|A(\mathbf{Q})|^2}{(1 - e^{iQ_z a_3} e^{-\beta})(1 - e^{-iQ_z a_3} e^{-\beta})}$$

$$Q_z = q_z + 2\pi l/a_3 \quad I^{\text{CTR}} \approx \frac{|A(\mathbf{Q})|^2}{q_z^2 a_3^2 + \beta^2}$$

Velký monokrystal



z_0 posun horní atomové vrstvy

Epitaxní vrstvy

$$J(\mathbf{Q}) = I_i K^2 \frac{4(\pi r_{\text{el}} C)^2}{V_{\text{cell}}^2} \sum_{\mathbf{g}_{\parallel}} \delta^{(2)}(\mathbf{Q}_{\parallel} - \mathbf{g}_{\parallel}) \times$$

$$\times \left| F_{\text{cell}}(\mathbf{Q}) \sum_{g_z} G_{\text{cryst}}(Q_z - g_z) \right|^2.$$

$$G_{\text{cryst}}(q_z) = \int_{-T}^0 dz e^{-iq_z z} = \frac{i}{q_z} (1 - e^{-iq_z T}) \equiv$$

$$e^{-iq_z T/2} T \text{sinc} \left(\frac{q_z T}{2} \right),$$

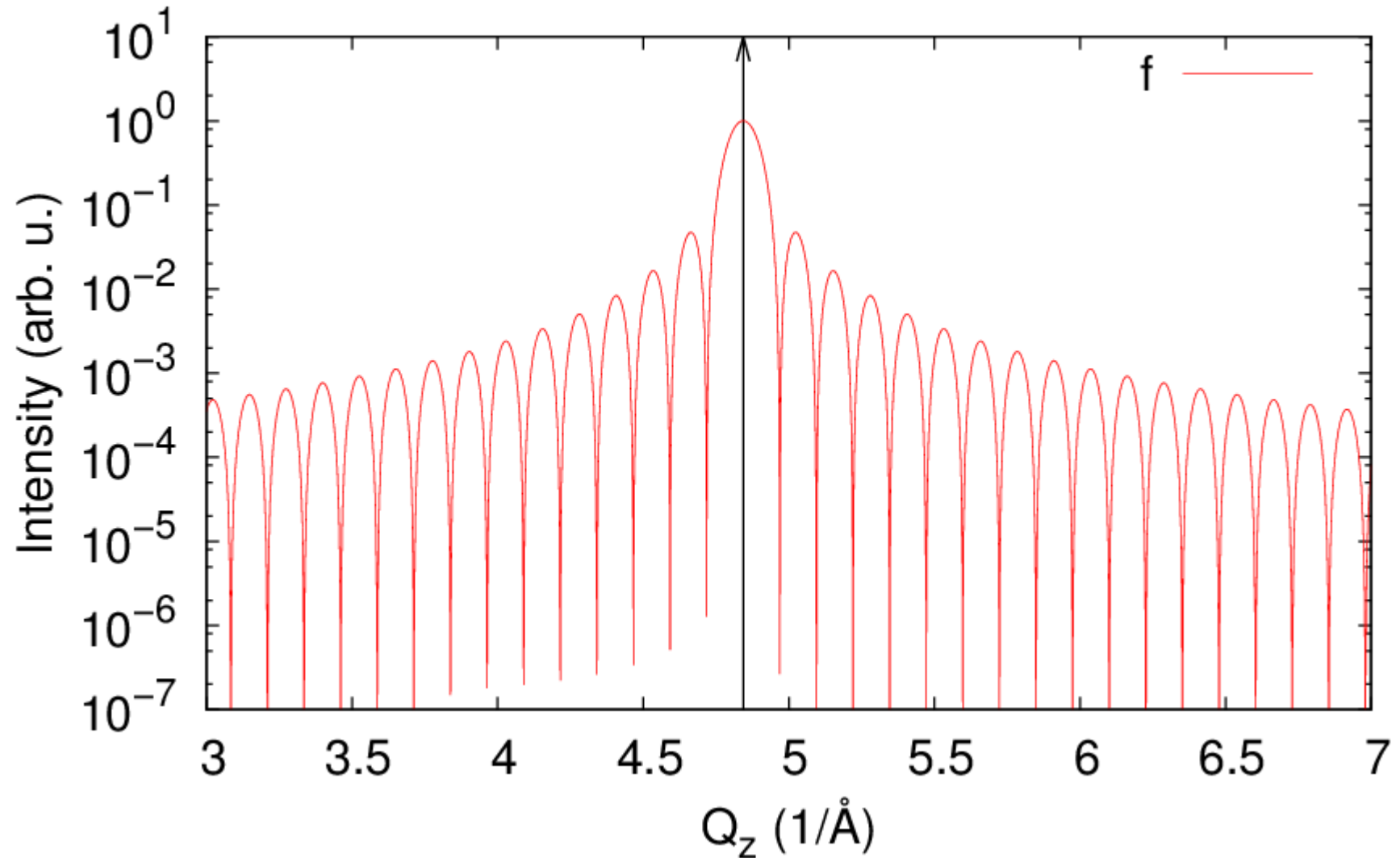
$$J(\mathbf{Q}) = I_i K^2 \frac{4(\pi r_{\text{el}} C)^2}{V_{\text{cell}}^2} \delta^{(2)}(\mathbf{Q}_{\parallel} - \mathbf{h}_{\parallel}) |F_{\text{cell}}(\mathbf{h}) G_{\text{cryst}}(Q_z - h_z)|^2$$

$$\chi(\mathbf{r}) = \sum_{\mathbf{g}} \chi_{\mathbf{g}} e^{i\mathbf{g} \cdot \mathbf{r}} \quad \chi_{\mathbf{g}} = -\frac{r_{\text{el}} C \lambda^2}{\pi V_{\text{cell}}} \sum_s f_s(\mathbf{g}) e^{-i\mathbf{g} \cdot \mathbf{r}_s}$$

Epitaxní vrstvy

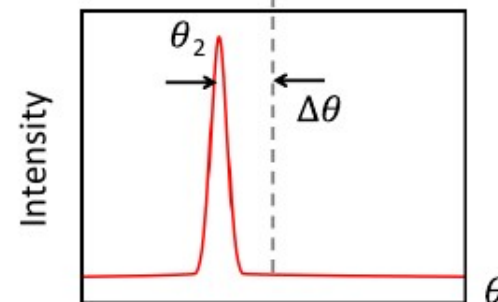
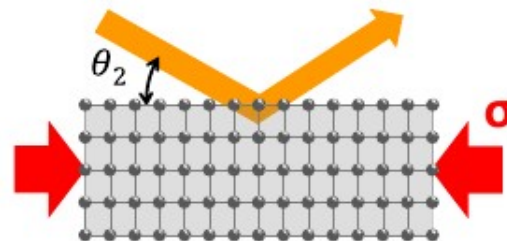
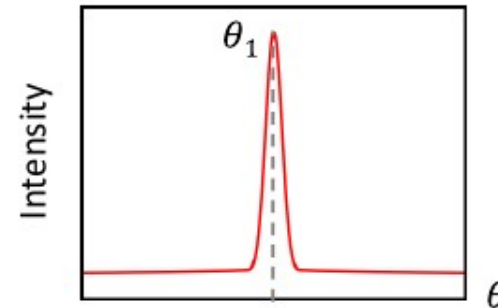
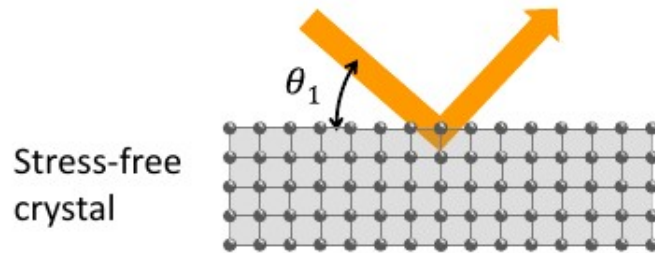
Jednoduchá vrstva, šipka poloha $2\pi/a$

$$T_a = 50\text{Å}, a_a = 5.189\text{Å}$$



Epitaxní vrstvy

Principle of X-ray diffraction based stress/strain analysis



- X-ray diffraction uses the crystal lattice as a “strain gauge”
- The relation between the lattice parameter and diffraction angle is defined by Bragg’s law, $2d \sin \theta_B = n\lambda$
- Most sensitive stress/strain analysis method for semi. (ITRS 2011)

Epitaxní vrstvy

$$\Delta Q_z = \frac{2\pi}{T}$$

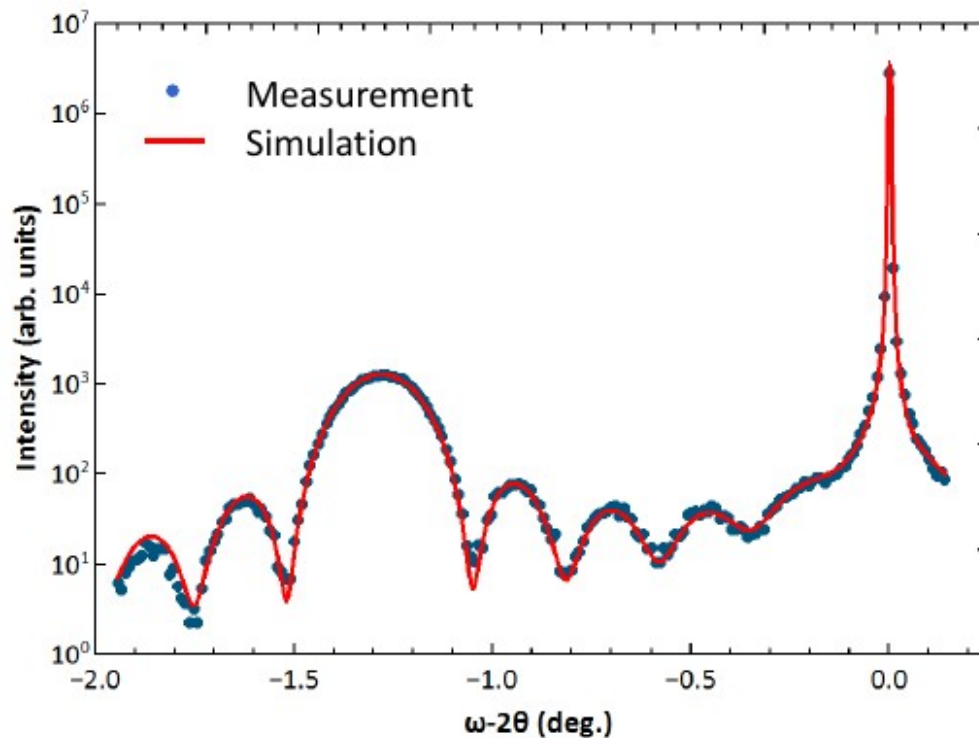
$$\Delta\eta_i = \lambda \frac{\gamma h}{\sin(2\Theta_B)T}$$

$$\Delta\eta_i = \frac{\lambda}{2T \cos \Theta_B}$$

Epitaxní vrstvy



Example: Fully strained SiGe epilayer



Symmetric 004 reflection from 22.5 nm epitaxial film of $\text{Si}_{1-x}\text{Ge}_x$ with $x = 49\%$ on a Si(001) substrate

- Composition / strain determined from measured lattice misfit
- Misfit normal to surface from layer peak position
$$\Delta d/d = -\Delta\omega \cot \theta_B$$
- Thickness from interference fringe period
$$t = \lambda / (2\Delta\omega_f \cos \theta_B)$$
- No dependence on uncertain materials parameters

Epitaxní vrstvy

Common Bragg diffraction geometries and anatomy of a HRXRD curve



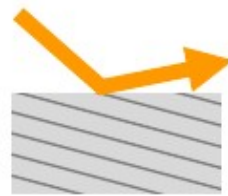
Symmetric geometry



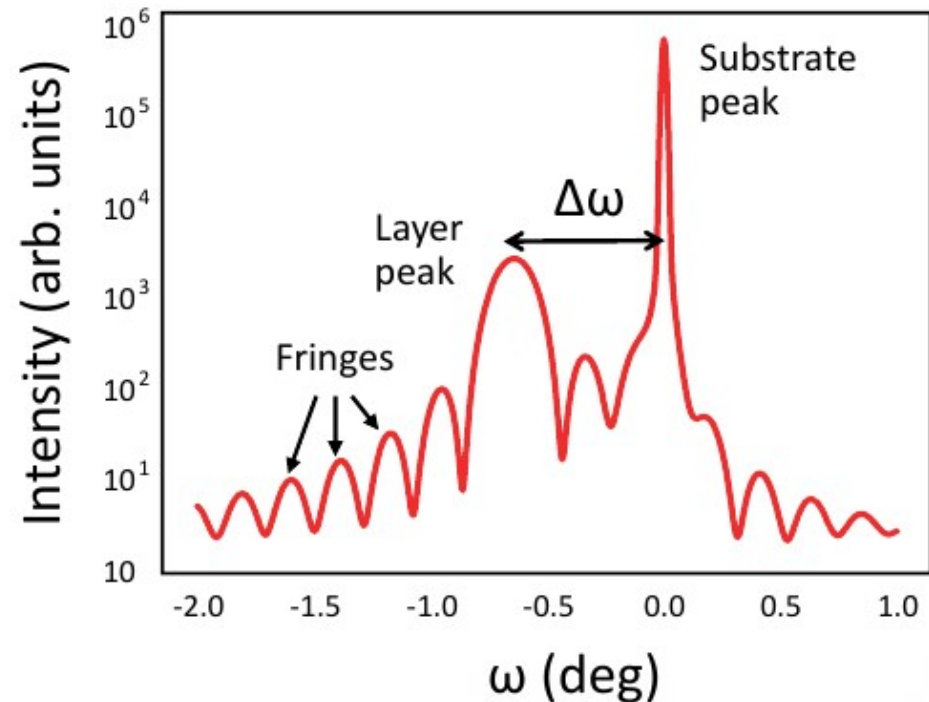
Asymmetric geometries



Glancing incidence



Glancing exit



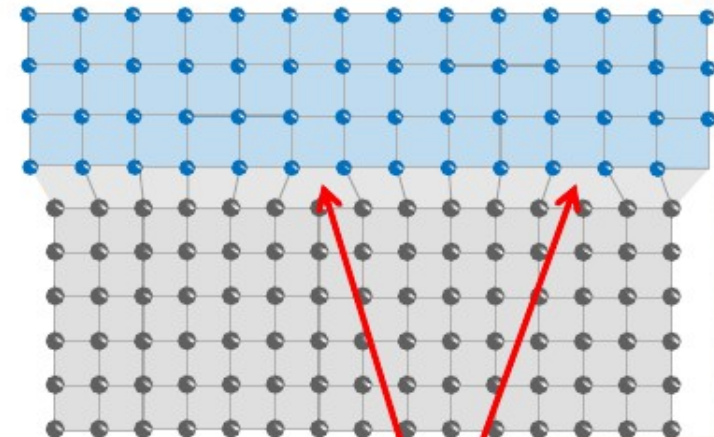
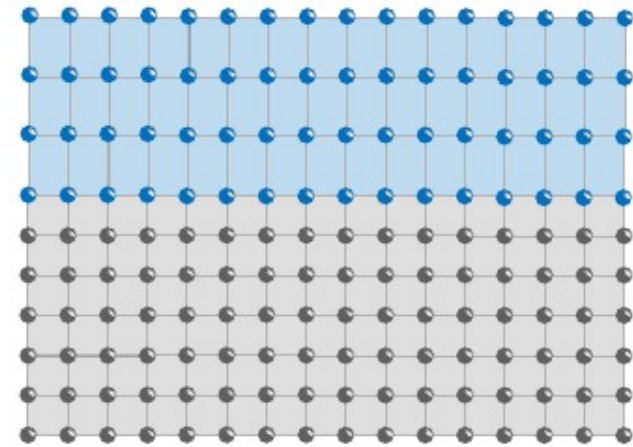
- Symmetric Bragg geometry is sensitive to lattice parameter perpendicular to the surface
- Asymmetric geometries are also sensitive to the lattice parameters both parallel and perpendicular to the surface

Epitaxní vrstvy



Lattice deformation in epitaxial thin-films

- If the lattice mismatch to the substrate and/or thickness is small, then an epilayer can be strained so that the in-plane lattice parameter is equal to that of the substrate (fully strained)
 - Tetragonal distortion of the unit cell
 - For large mismatch or thickness, it may become energetically favorable to relax
 - Creation of dislocations and/or roughening
- ... more on this later



Misfit
dislocations

Epitaxní vrstvy

$$\varepsilon_{\parallel} = \frac{a_{\parallel} - a_0}{a_0}, \quad \varepsilon_{\perp} = \frac{a_{\perp} - a_0}{a_0}.$$

$$\varepsilon_{\perp} = -2 \frac{\nu}{1 - \nu} \varepsilon_{\parallel}.$$

$$a_0 = \frac{(1 - \nu)a_{\perp} + 2\nu a_{\parallel}}{1 + \nu}.$$

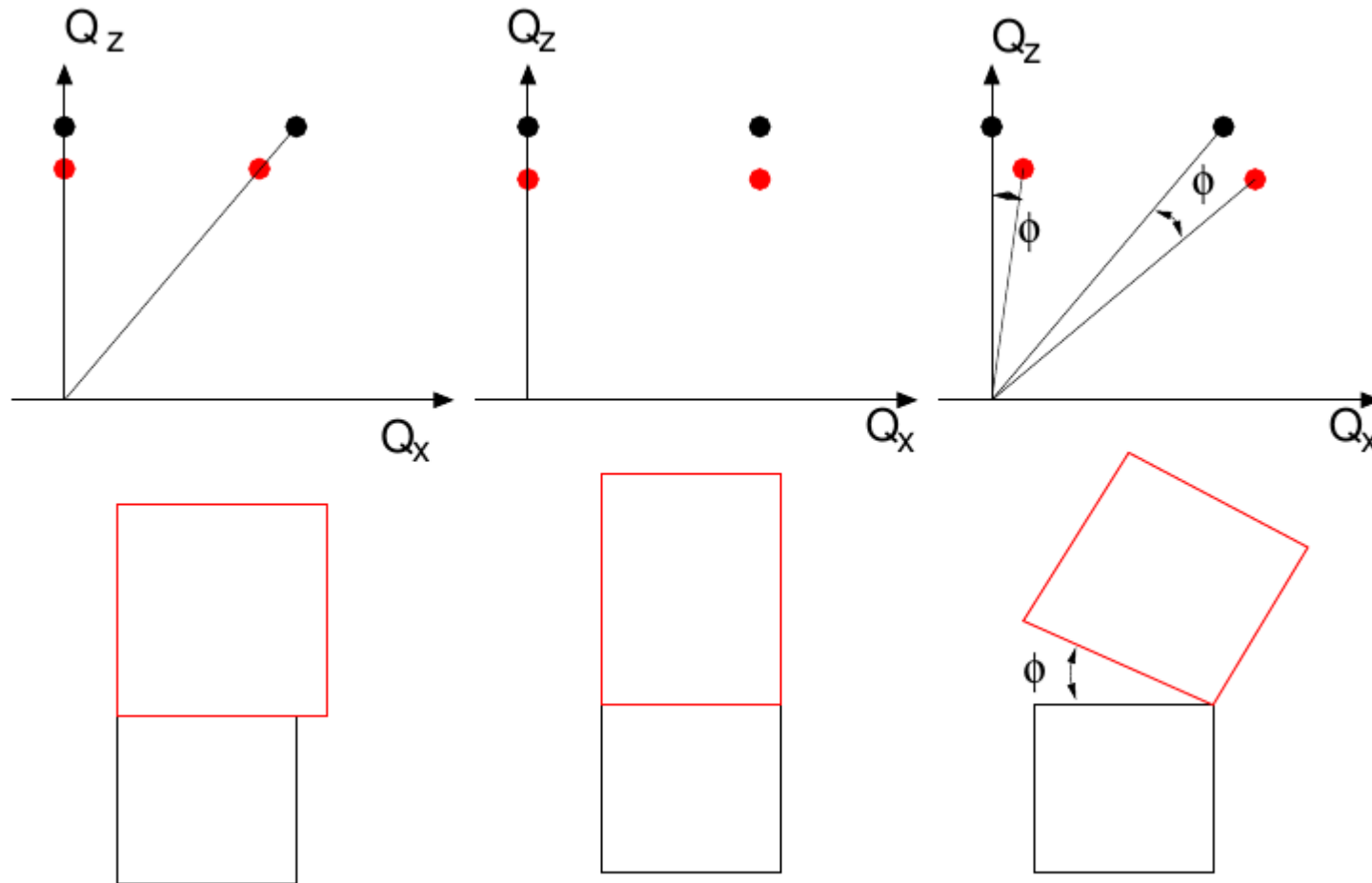
$$\nu_{001} = \frac{C_{12}}{C_{11} + C_{12}}, \quad \nu_{111} = \frac{1}{2} \frac{C_{11} + 2C_{12} - 2C_{44}}{C_{11} + 2C_{12} + C_{44}}$$

$$R = \frac{a_{L\parallel} - a_S}{a_{L\infty} - a_S}$$

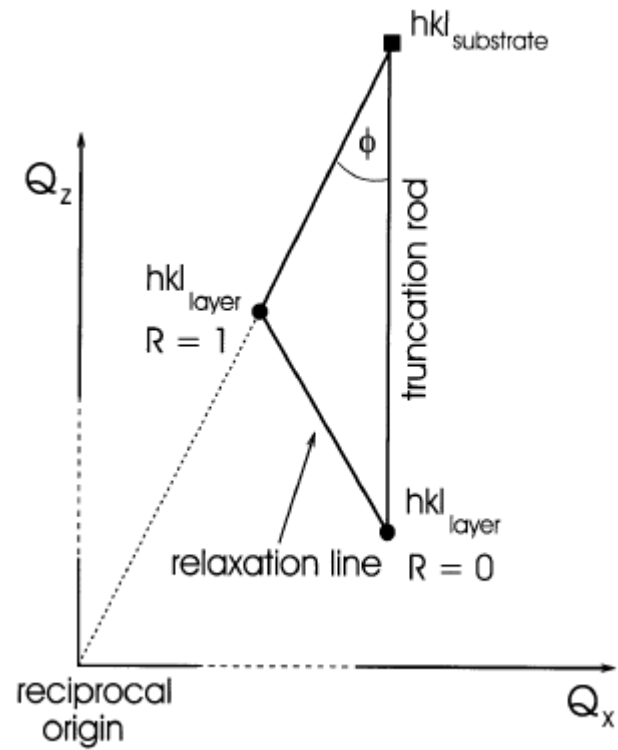
$$a_r = \sqrt{\frac{a_{\perp}^2 + 2a_{\parallel}^2}{3}}, \quad \cos \alpha_r = \frac{a_{\perp}^2 - a_{\parallel}^2}{a_{\perp}^2 + 2a_{\parallel}^2}$$

Epitaxní vrstvy

Polohy difrakčních maxim pro různé vzájemné polohy mřížky vrstvy a substrátu



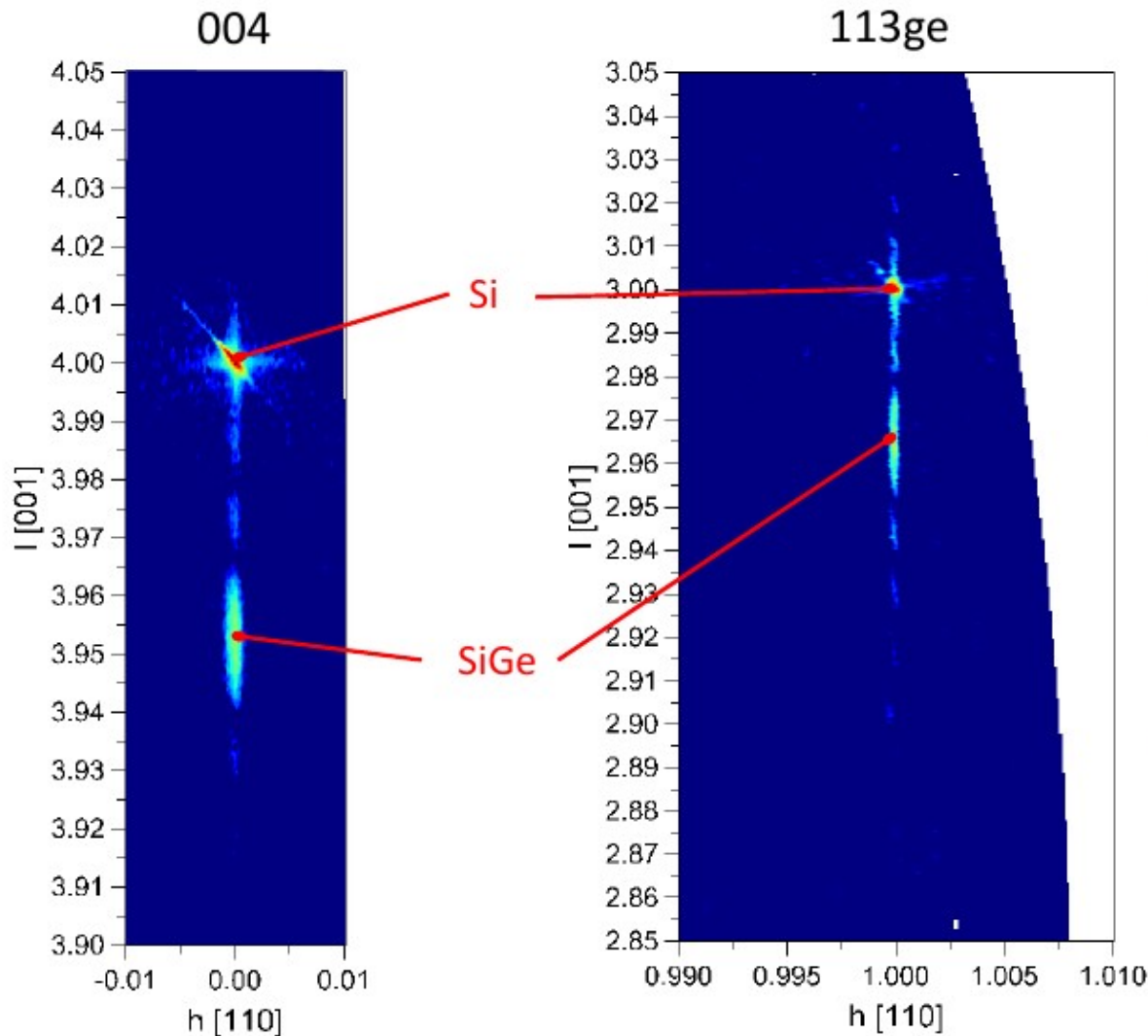
Epitaxní vrstvy



Epitaxní vrstvy

RSMs from fully strained epitaxial thin-films

37.6 nm $\text{Si}_{0.81}\text{Ge}_{0.19}$ on Si(001)

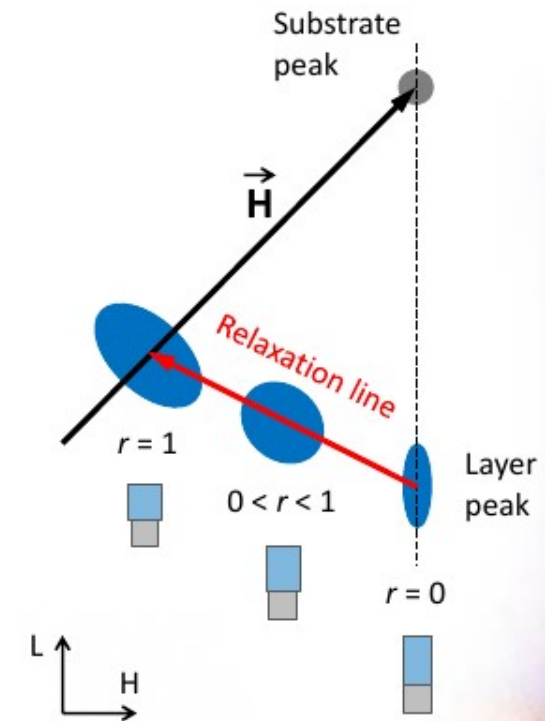
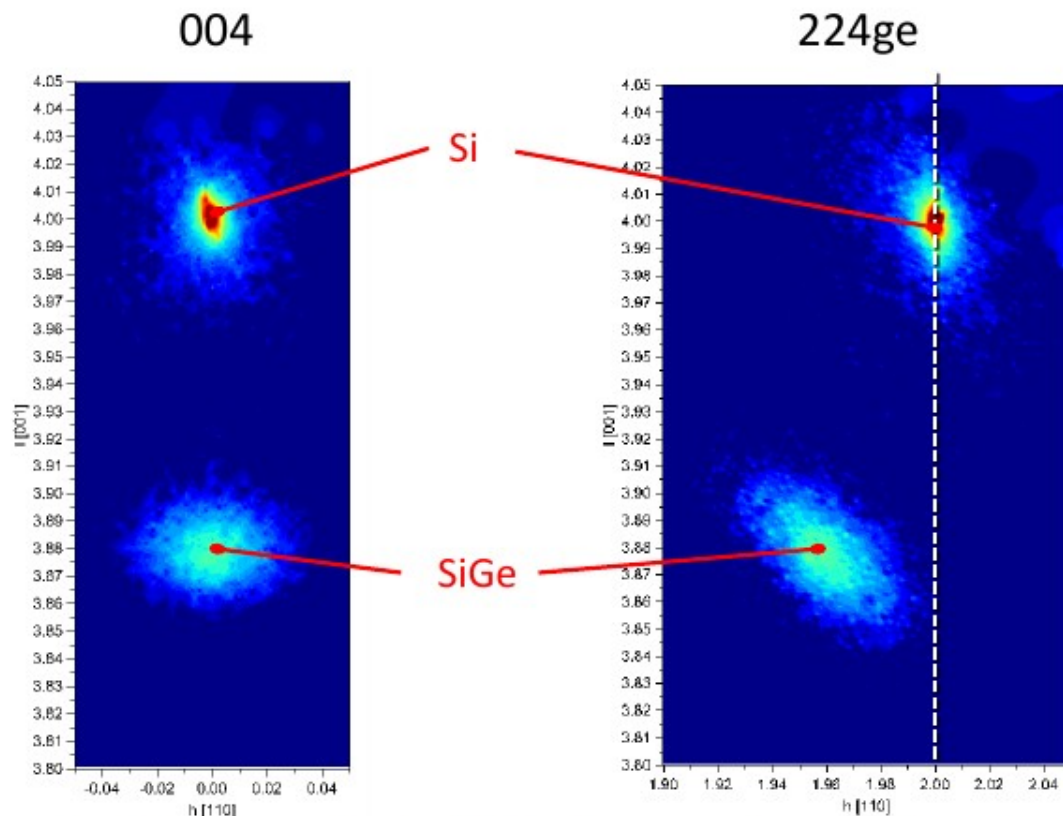


- Layer peak position gives the lattice parameters
$$\Delta a_{\perp}/a = \Delta L/L$$
$$\Delta a_{\parallel}/a = \Delta H/H$$
- Composition and relaxation can be obtained
- Peak in the asymmetric RSM is located at $H = 1$ indicating the layer is fully strained ($a_{\text{SiGe},\parallel} = a_{\text{Si}}$)
- Thickness fringes are visible in the L direction
$$t \propto 1/\Delta L_{\text{fringes}}$$

Epitaxní vrstvy

RSMs from relaxed epitaxial thin-films

~35 nm $\text{Si}_{0.33}\text{Ge}_{0.67}$ ($R = 70\%$) on Si(001)



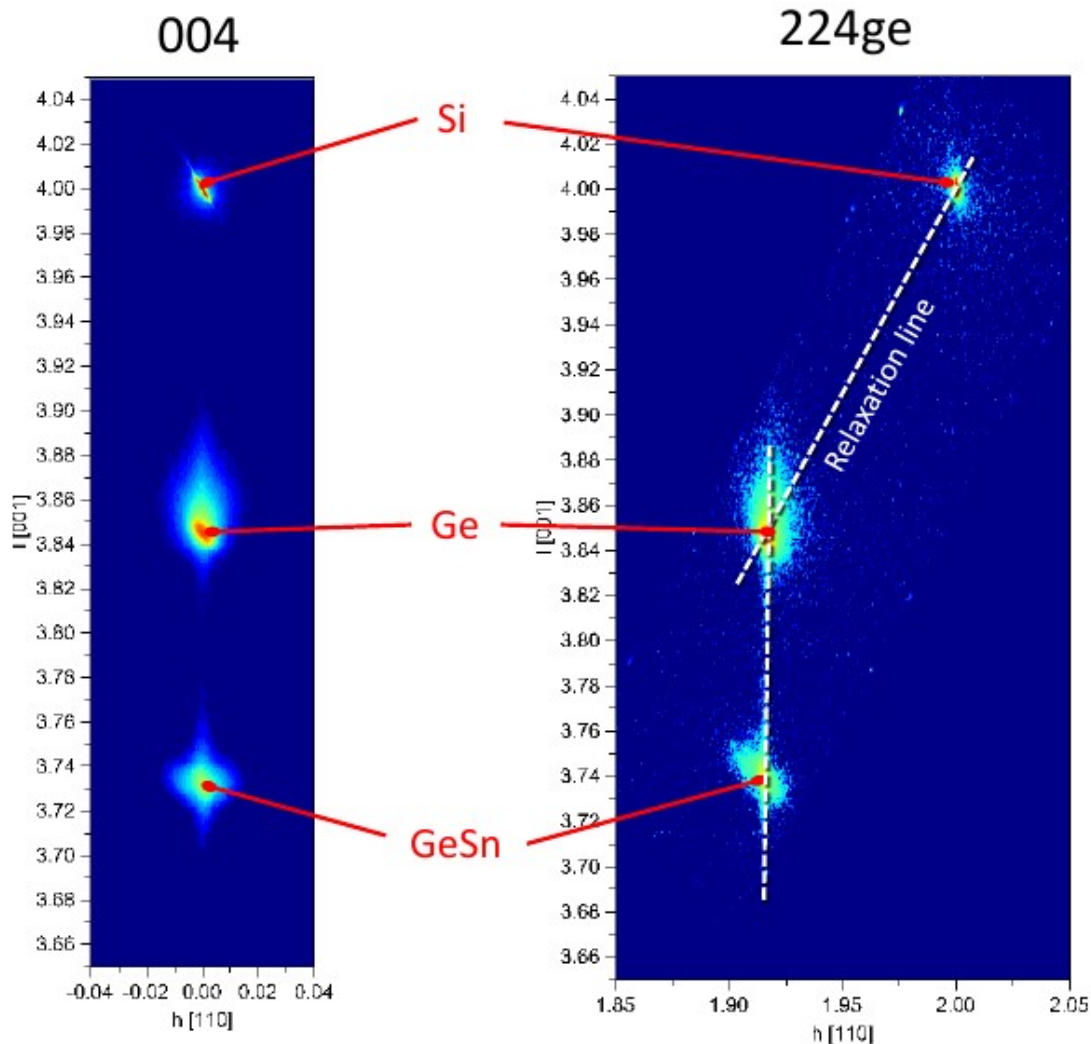
- SiGe peak is shifted away from $H=2$ in the asymmetric 224ge map indicating relaxation ($a_{\text{SiGe},||} > a_{\text{Si}}$)
- Peak is broadened due to dislocations, $w(H)/H \propto 1/\sqrt{\rho}$

Epitaxní vrstvy

RSMs from strained thin-films on strain relaxed buffers (SRBs)

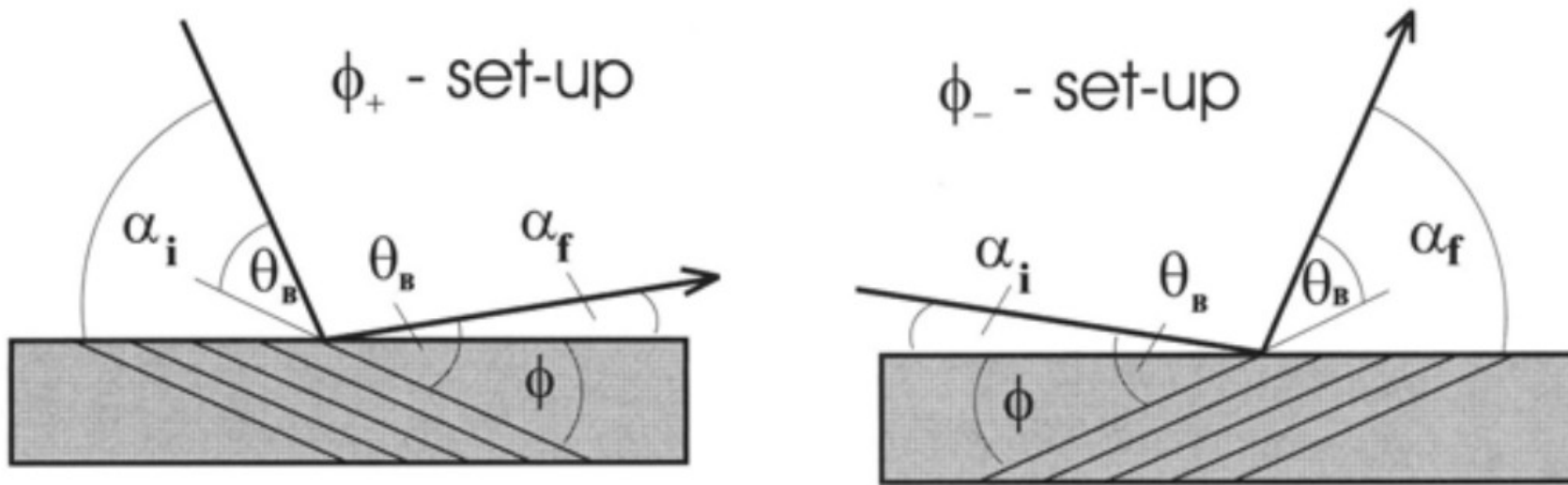


$\text{Ge}_{0.89}\text{Sn}_{0.11} / \text{Ge}$ on $\text{Si}(001)$



- Ge peak is shifted away from $H < 2$ in the asymmetric 224ge map indicating relaxation ($a_{\text{Ge},||} > a_{\text{Si}}$)
- GeSn peak is not shifted in H wrt to Ge peak ($a_{\text{GeSn},||} = a_{\text{Si}}$)
- Composition and relaxation of each layer can be obtained

Epitaxní vrstvy



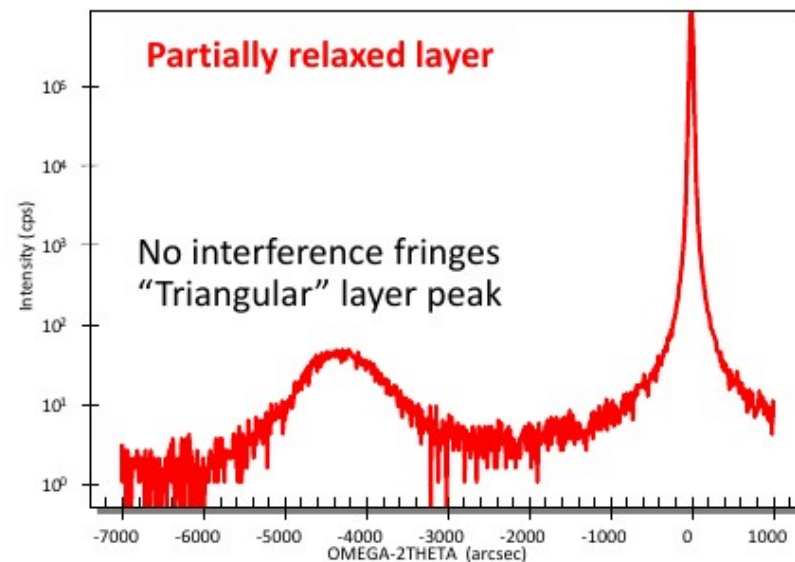
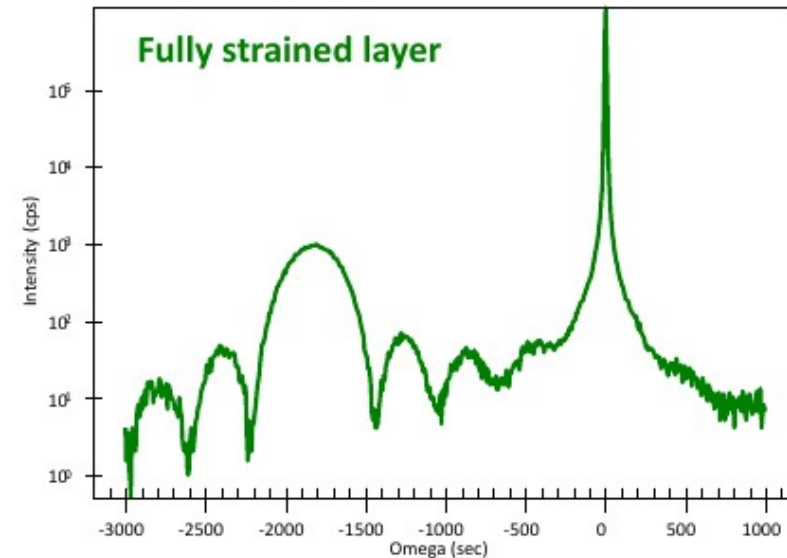
$$\delta_{L\perp} = \Delta\phi \tan \phi - \Delta\theta_B \cot \theta_B,$$
$$\delta_{L\parallel} = -\Delta\phi \cot \phi - \Delta\theta_B \cot \theta_B.$$

Epitaxní vrstvy

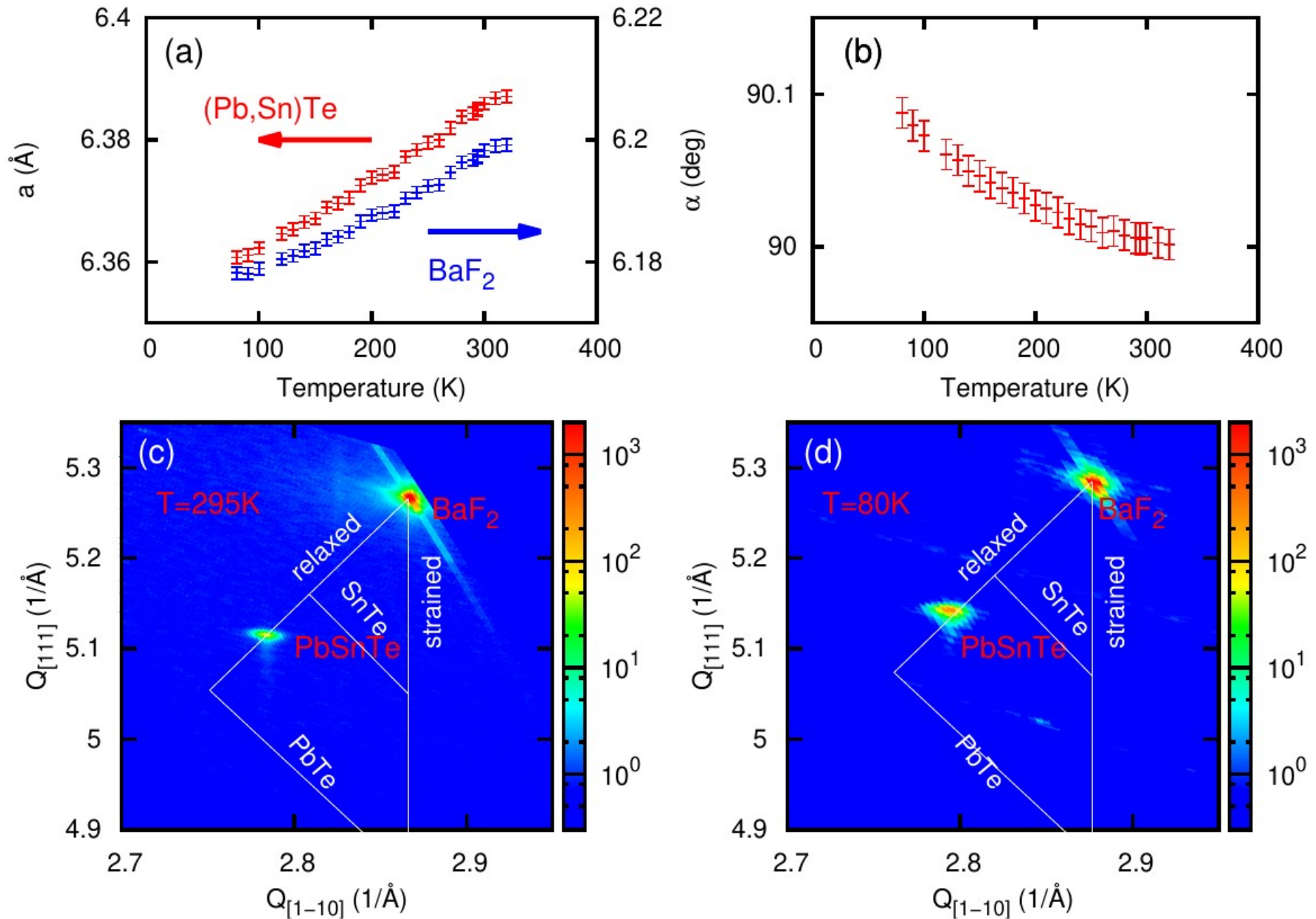
Comparison of HRXRD data from strained and relaxed SiGe epilayers



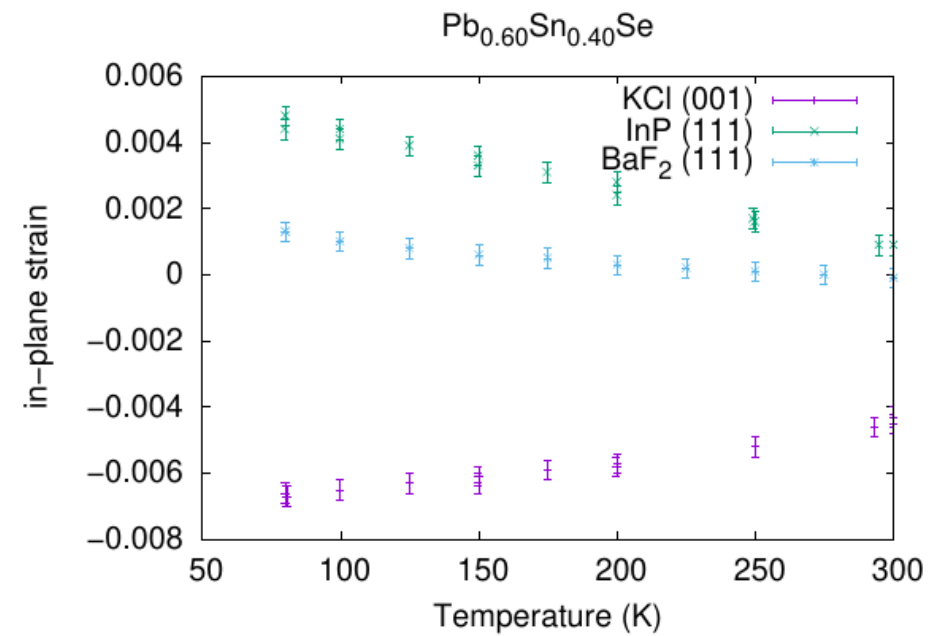
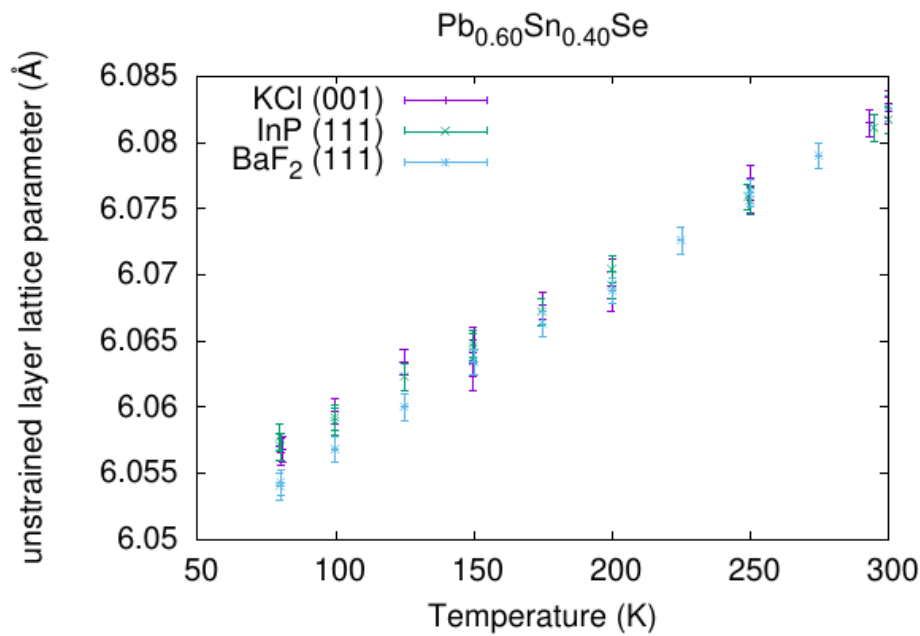
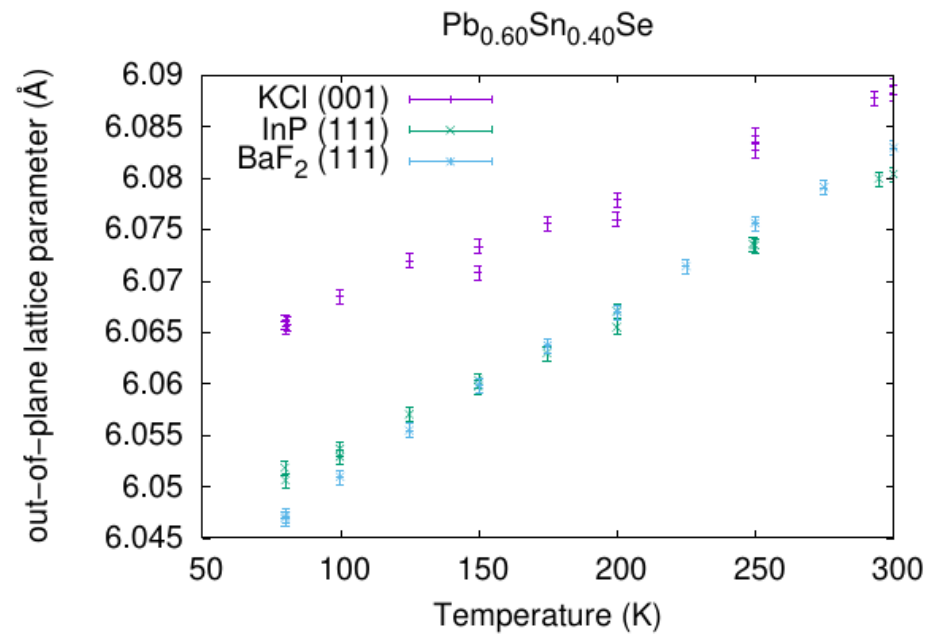
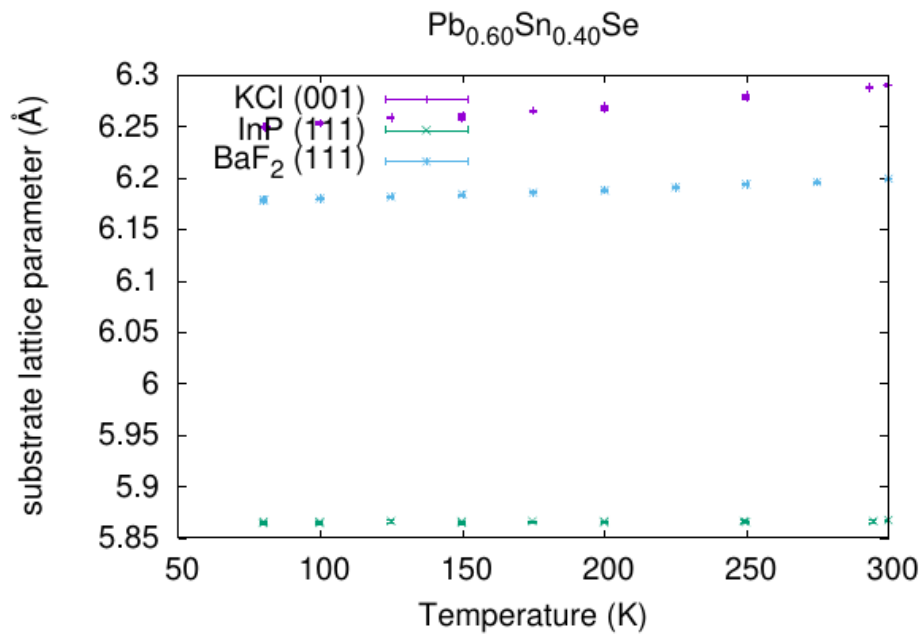
- Degradation of device performance and yield loss
 - Relaxed material has about 50% less strain than a pseudomorphic layer
 - Relaxed material will contain dislocations at the interface and in the layer - increased leakage?
- HRXRD provides a unique, automated solution for strain metrology and assessment of lattice defectivity



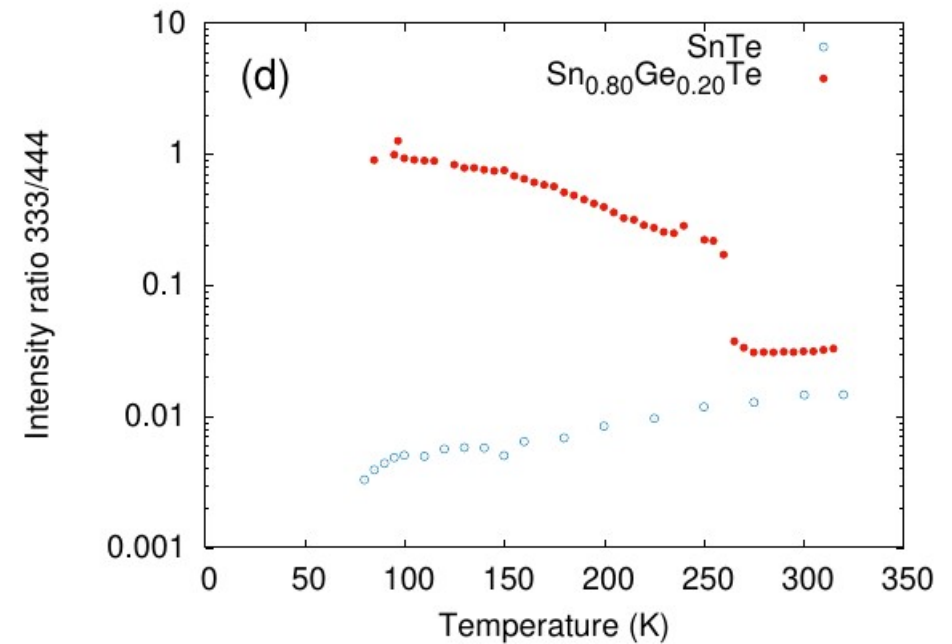
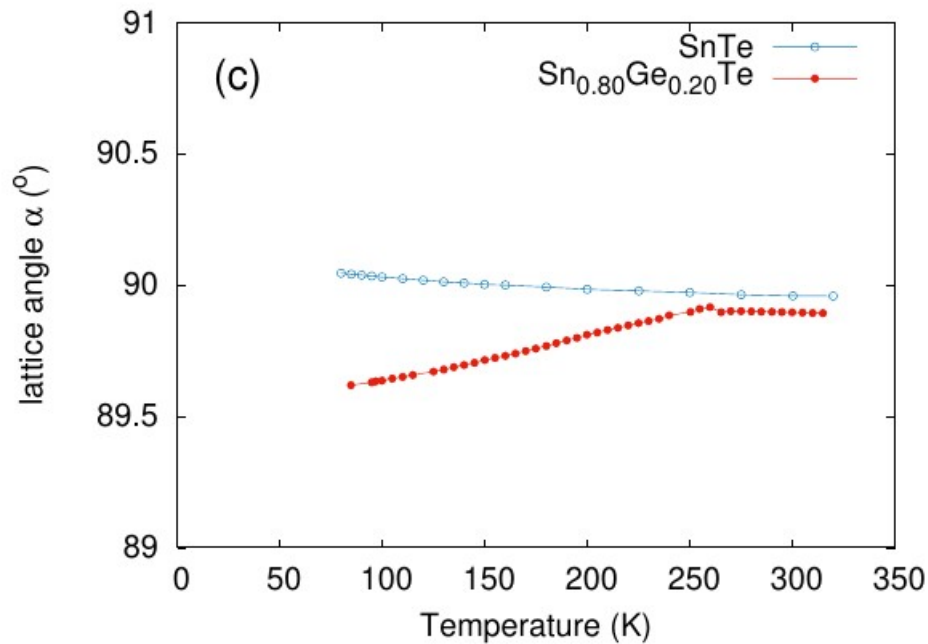
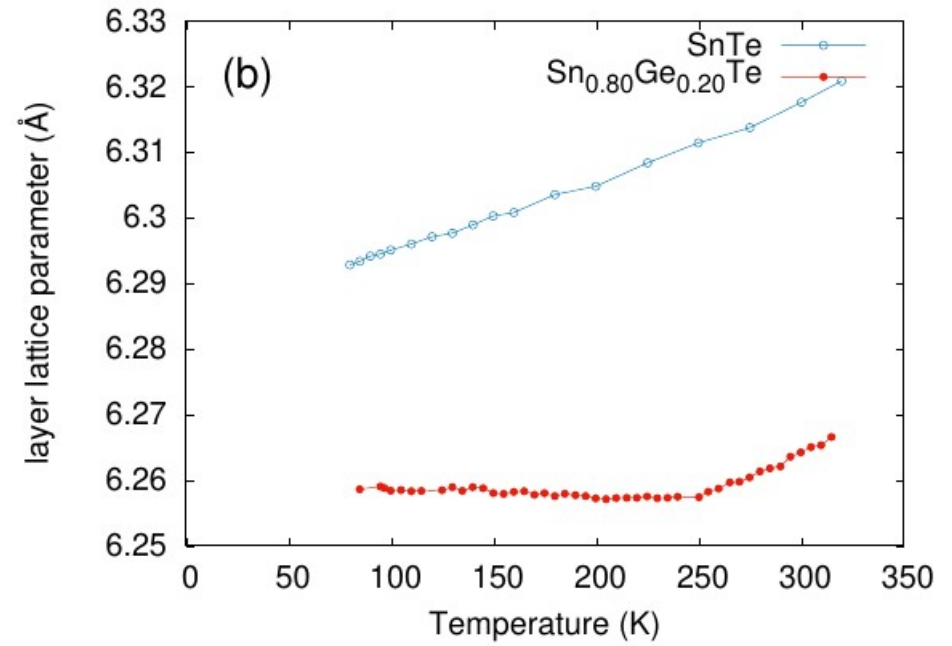
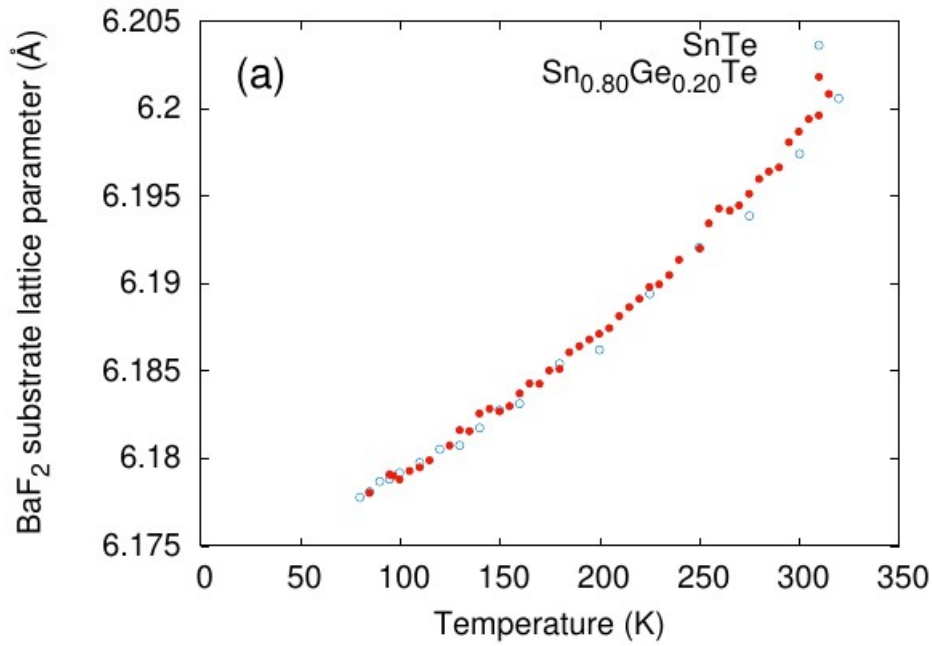
Epitaxní vrstvy



Epitaxní vrstvy



Epitaxní vrstvy



Epitaxní vrstvy

$$F_{n,\text{cell}}(\mathbf{Q}) = e^{-i\mathbf{Q}\cdot\mathbf{u}_n} \sum_s f_s(\mathbf{Q}) e^{-i\mathbf{Q}\cdot(\mathbf{r}_s+\mathbf{u}_{ns})}$$

$$F_{n,\text{cell}}(\mathbf{Q}) = e^{-i\mathbf{Q}\cdot\mathbf{u}_n} F_{\text{cell}}(\mathbf{Q})$$

$$E(\mathbf{r}) = -iE_i \frac{r_{\text{el}}C}{2\pi V_{\text{cell}}} \int \frac{d^2\mathbf{K}_{\parallel}}{K_z} e^{i\mathbf{K}\cdot\mathbf{r}} F_{\text{cell}}(\mathbf{Q}) \times$$
$$\times \sum_{\mathbf{g}} \int_{V_{\text{cryst}}} d^3\mathbf{r}' e^{-i(\mathbf{Q}-\mathbf{g})\cdot\mathbf{r}'} e^{-i\mathbf{Q}\cdot\mathbf{u}(\mathbf{r}')}, \quad \mathbf{Q} = \mathbf{K} - \mathbf{K}_i$$

Epitaxní vrstvy

$$I = I_i \frac{4(\pi r_{el} C)^2}{V_{cell}^2} \sum_{g_{\parallel}} \left| \frac{1}{K_{gz}} \sum_{g_z} \sum_{n=1}^N F_{cell}^{(n)}(g_{\parallel}, K_{gz} - K_{iz}) \times \right.$$

$$\left. \times G_{layer}^{(n)}(K_{gz} - \tilde{K}_{gz}) \right|^2$$

$$G_{layer}^{(n)}(Q_z) = \int_{z_{n+1}}^{z_n} dz e^{-iQ_z(z+u(z))}$$

$$\langle a \rangle = \frac{n_A a_A + n_B a_B}{n_A + n_B}$$

$$u_B(z) = \delta_B \Delta z$$

$$\delta_{A,B} = (a_{A,B} - \langle a \rangle) / \langle a \rangle$$

$$u_A(z) = \delta_A \Delta z + (\delta_B - \delta_A) n_B \langle a \rangle$$

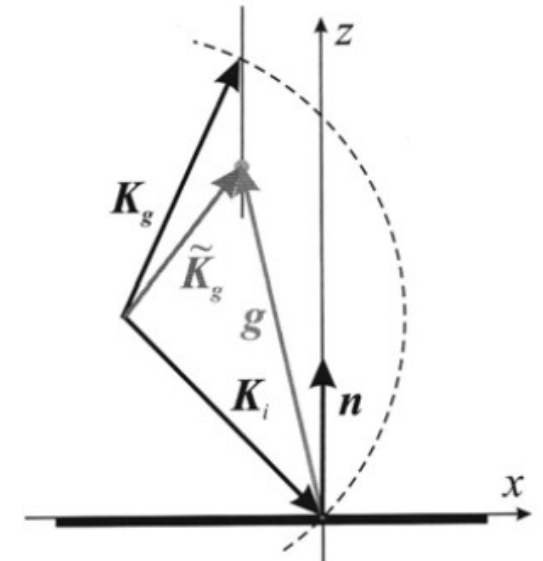
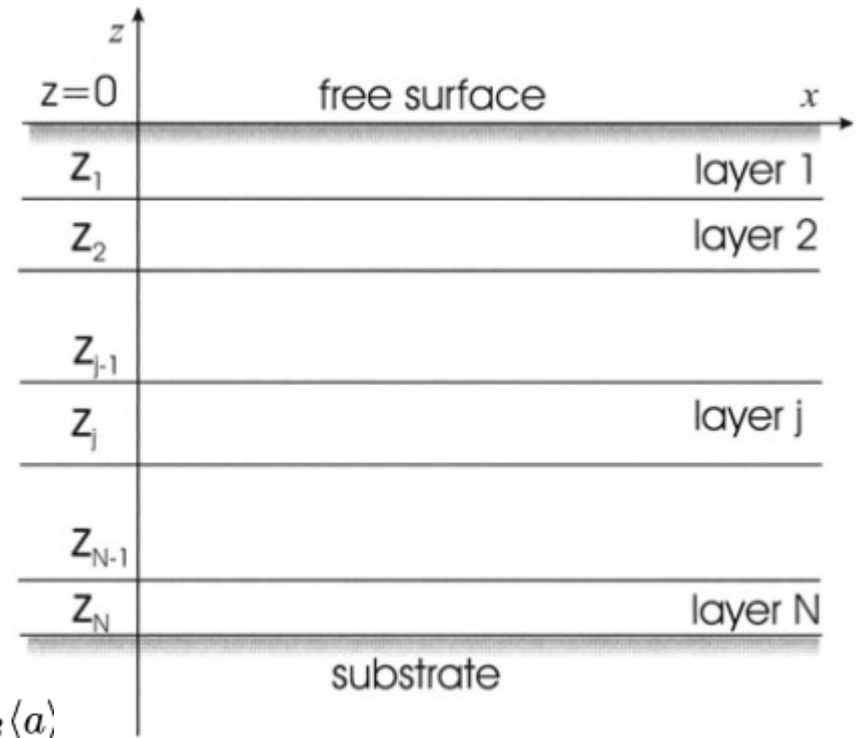
$$\Delta z = z - z_m$$

$$I = I_i \frac{4(\pi r_{el} C)^2}{V_{cell}^2} \sum_{g_{\parallel}} \left| \frac{1}{K_{gz}} \sum_{g_z} F_{period}(g_{\parallel}, K_{gz} - K_{iz}) \times \right.$$

$$\left. \times G_{multilayer}(K_{gz} - \tilde{K}_{gz}) \right|^2,$$

$$F_{period}(Q) = F_{cell}^{(B)}(Q) \frac{e^{-iq_B T_B} - 1}{-iq_B} + F_{cell}^{(A)}(Q) e^{-iq_B T_B} \frac{e^{-iq_A T_A} - 1}{-iq_A}$$

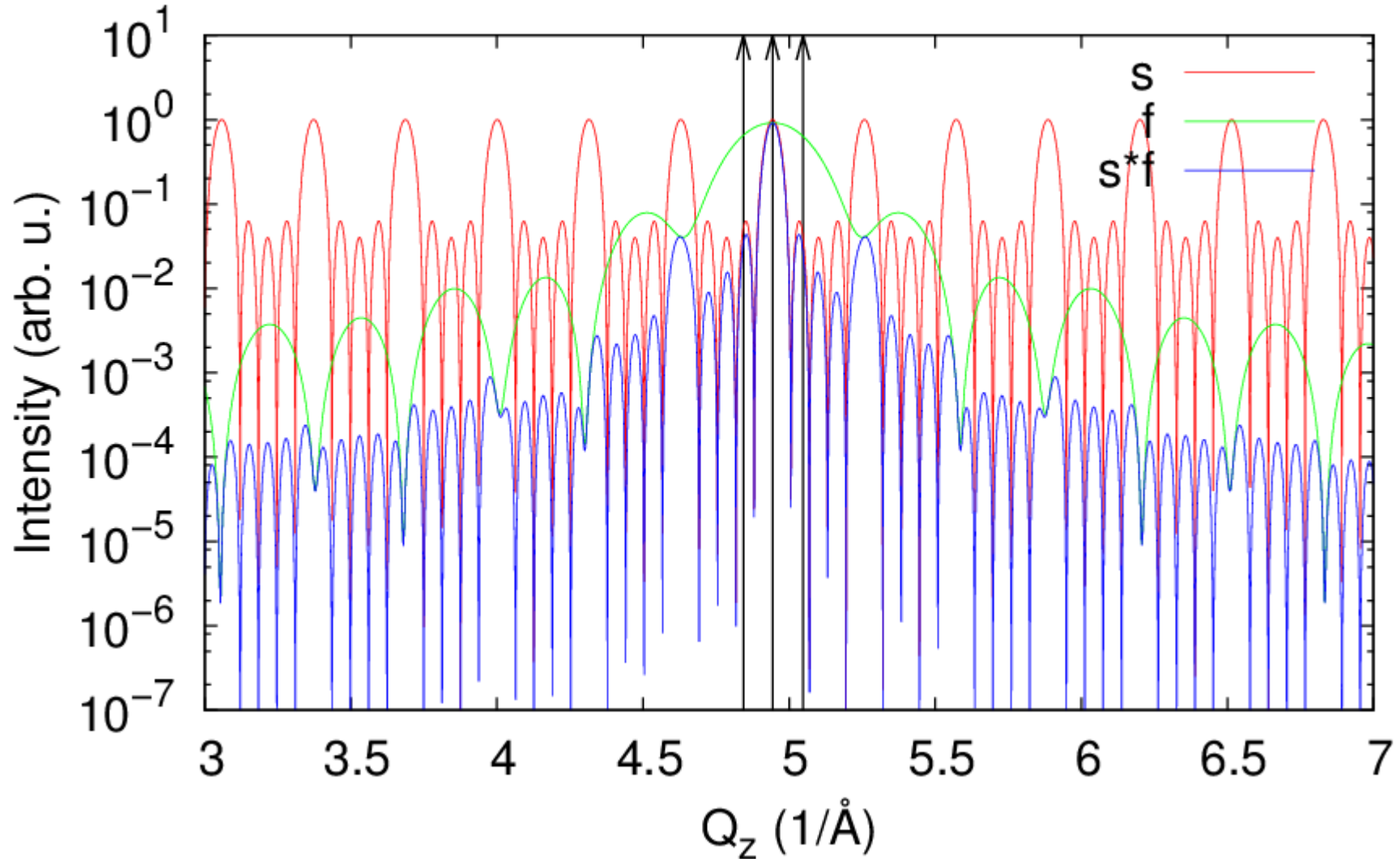
$$q_{A,B} = Q_z - g_z + Q_z \delta_{A,B} \quad G_{multilayer}(q) = e^{iqD} \frac{e^{iqT} - 1}{e^{iqD} - 1}, \quad q = K_{gz} - \tilde{K}_{gz}$$



Epitaxní vrstvy

Multivrstva s – geometrický faktor, f – strukturní faktor, sf – celková intenzita

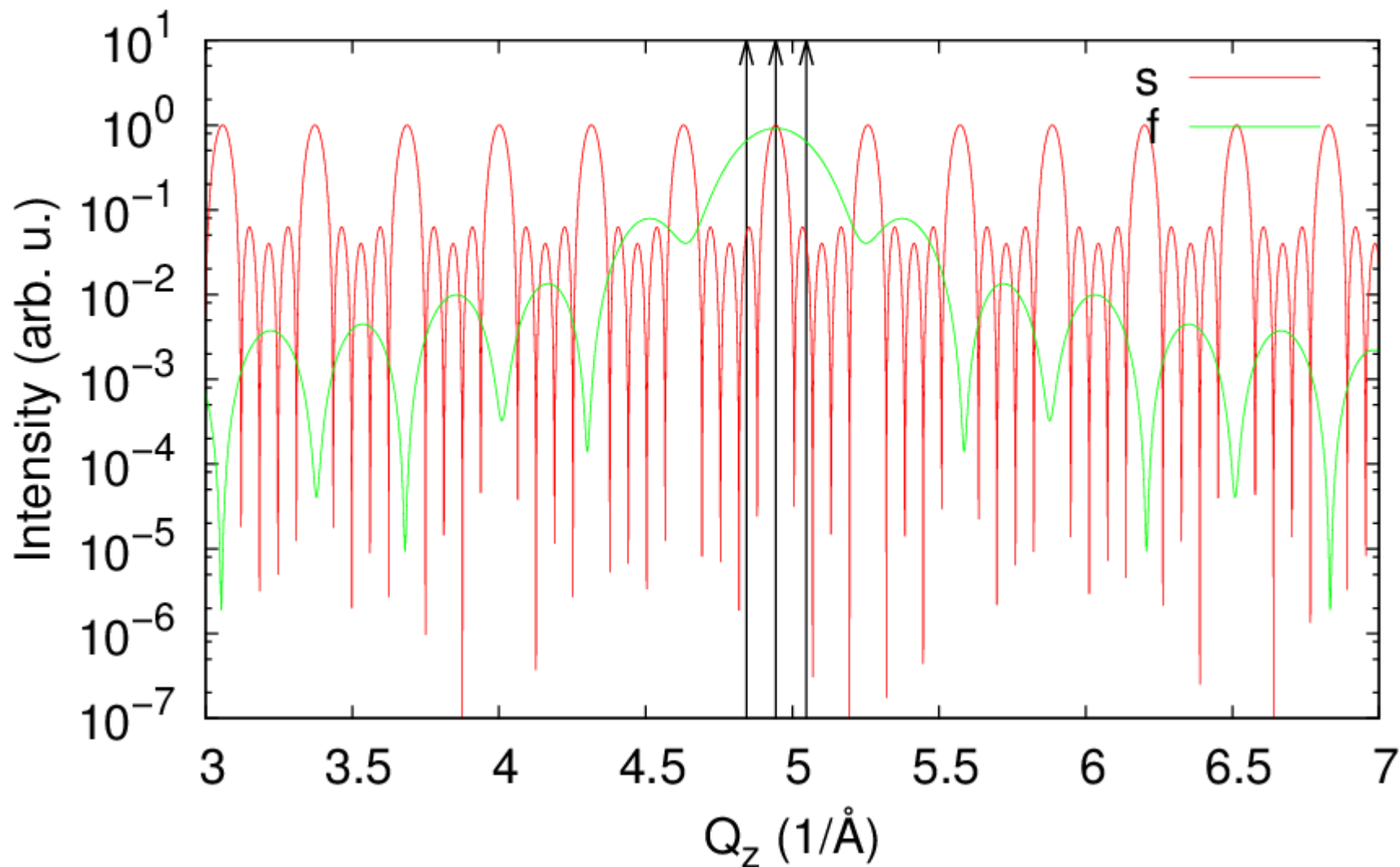
$$T_a=10\text{\AA}, T_b=10\text{\AA}, N=5, a_a=5.189\text{\AA}, a_b=4.979\text{\AA}$$



Epitaxní vrstvy

Multivrstva s – geometrický faktor, f – strukturní faktor, sf – celková intenzita

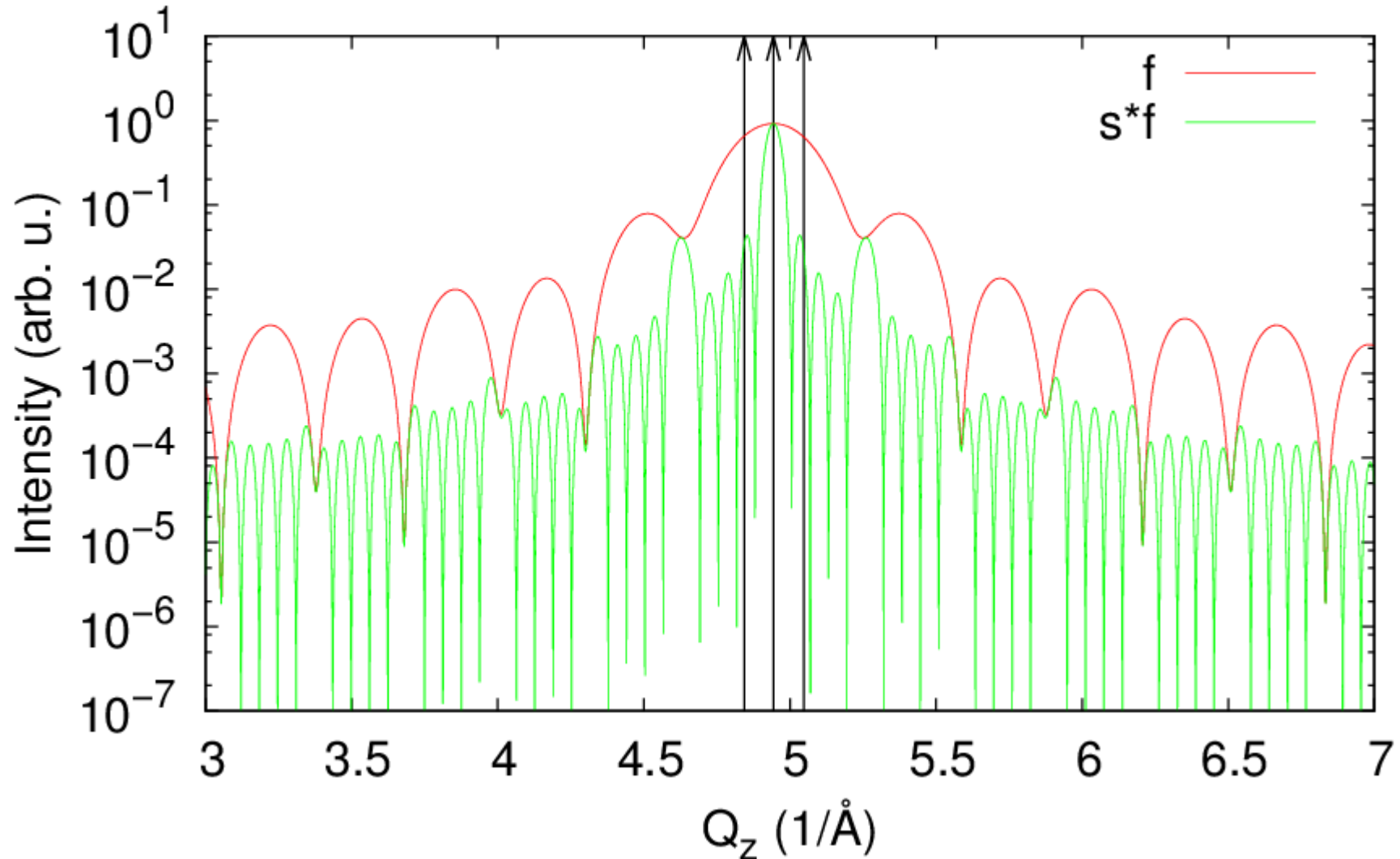
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Epitaxní vrstvy

Multivrstva s – geometrický faktor, f – strukturní faktor, sf – celková intenzita

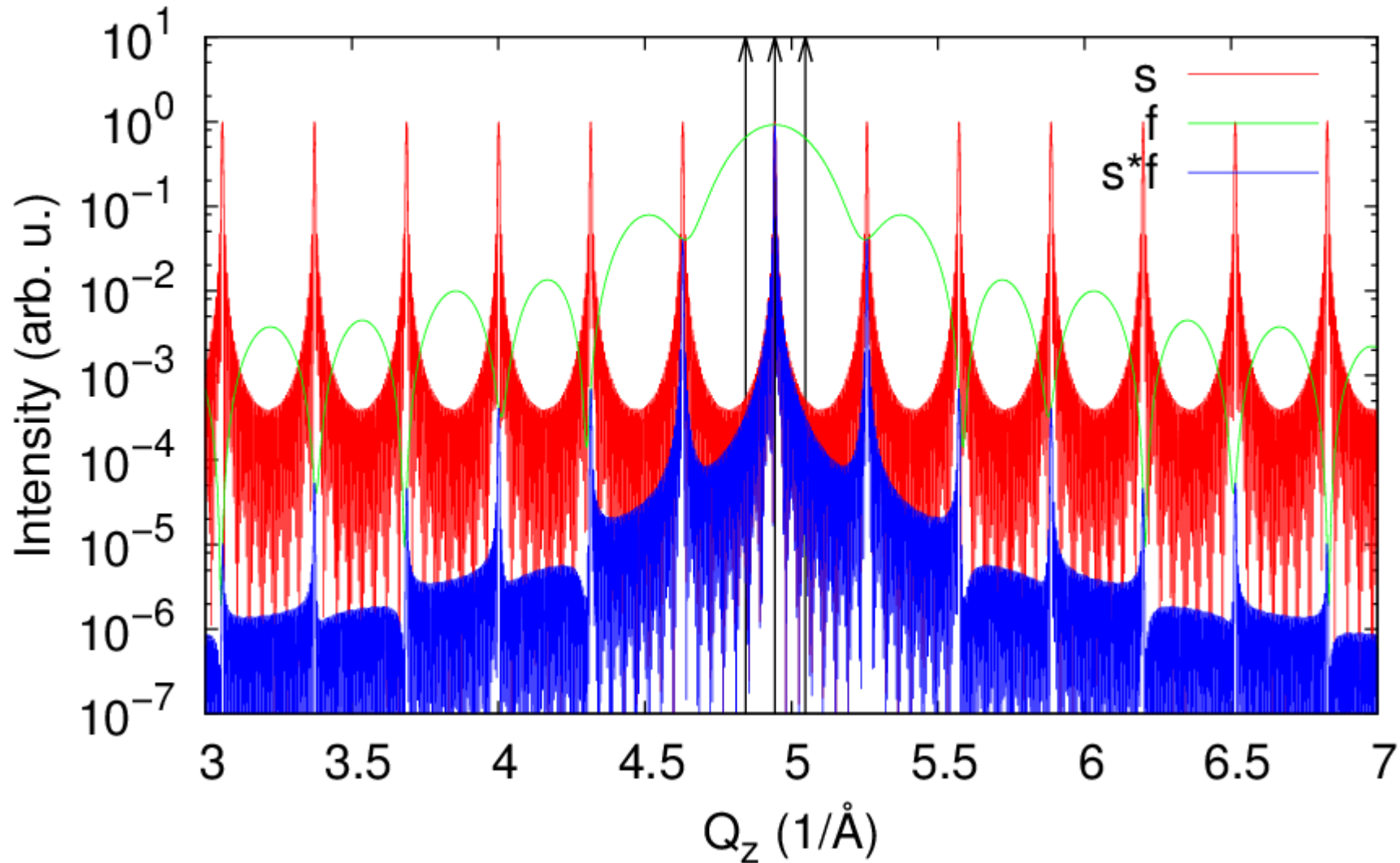
$$T_a=10\text{\AA}, T_b=10\text{\AA}, N=5, a_a=5.189\text{\AA}, a_b=4.979\text{\AA}$$



Epitaxní vrstvy

Multivrstva s – geometrický faktor, f – strukturní faktor, sf – celková intenzita

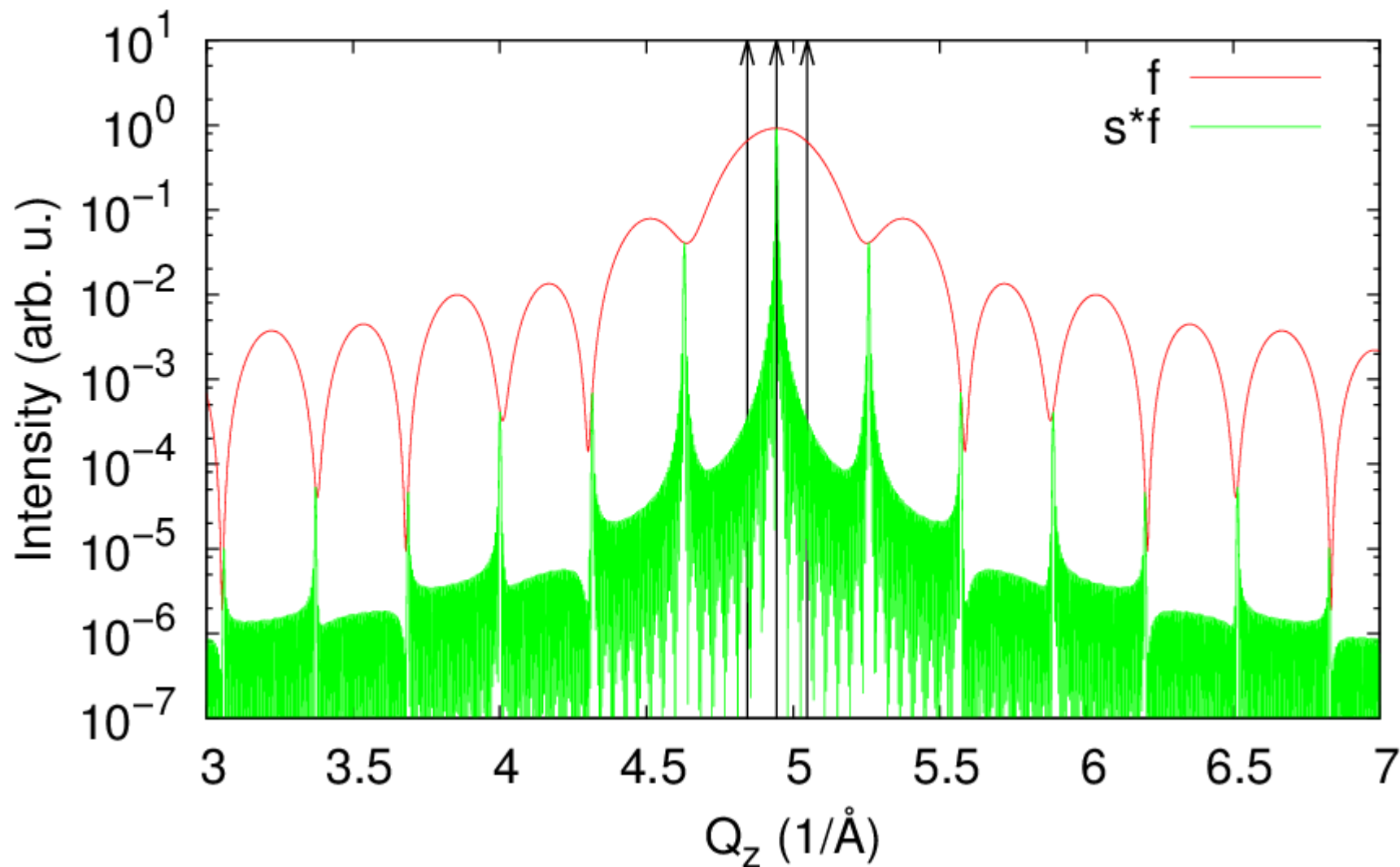
$$T_a=10\text{\AA}, T_b=10\text{\AA}, N=50, a_a=5.189\text{\AA}, a_b=4.979\text{\AA}$$



Epitaxní vrstvy

Multivrstva s – geometrický faktor, f – strukturní faktor, sf – celková intenzita

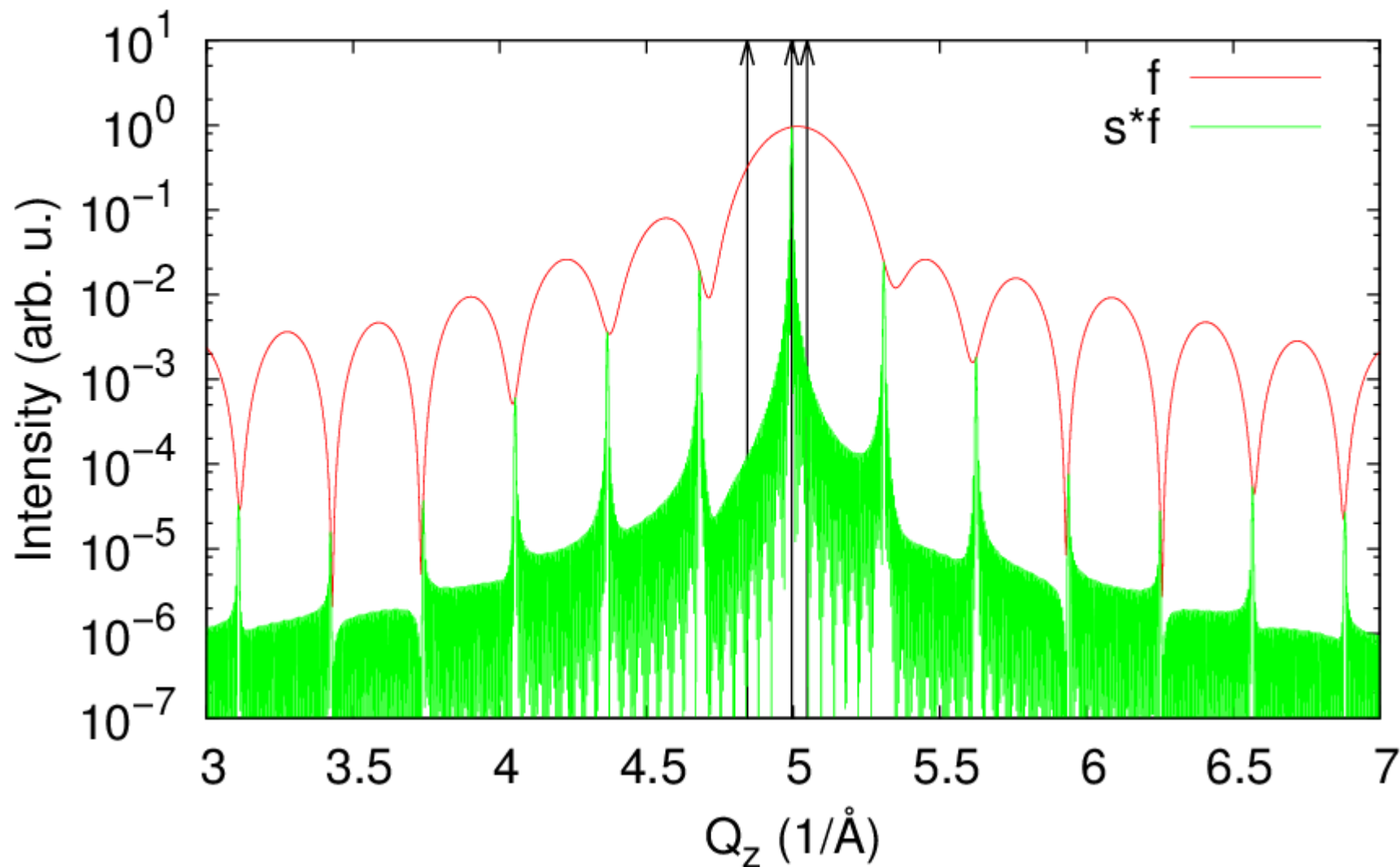
$$T_a=10\text{\AA}, T_b=10\text{\AA}, N=50, a_a=5.189\text{\AA}, a_b=4.979\text{\AA}$$



Epitaxní vrstvy

Multivrstva s – geometrický faktor, f – strukturní faktor, sf – celková intenzita

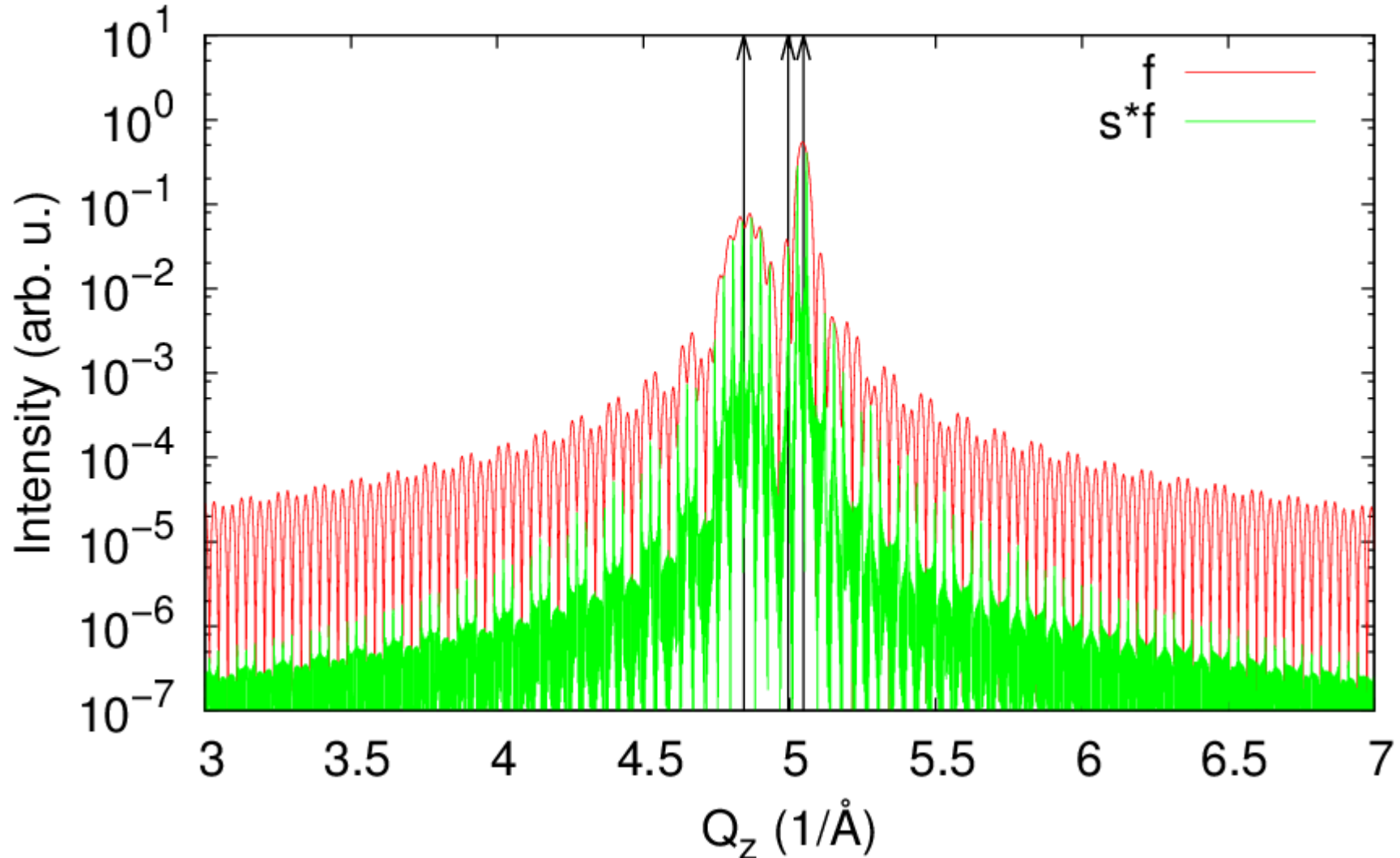
$$T_a=5\text{\AA}, T_b=15\text{\AA}, N=50, a_a=5.189\text{\AA}, a_b=4.979\text{\AA}$$



Epitaxní vrstvy

Multivrstva s – geometrický faktor, f – strukturní faktor, sf – celková intenzita

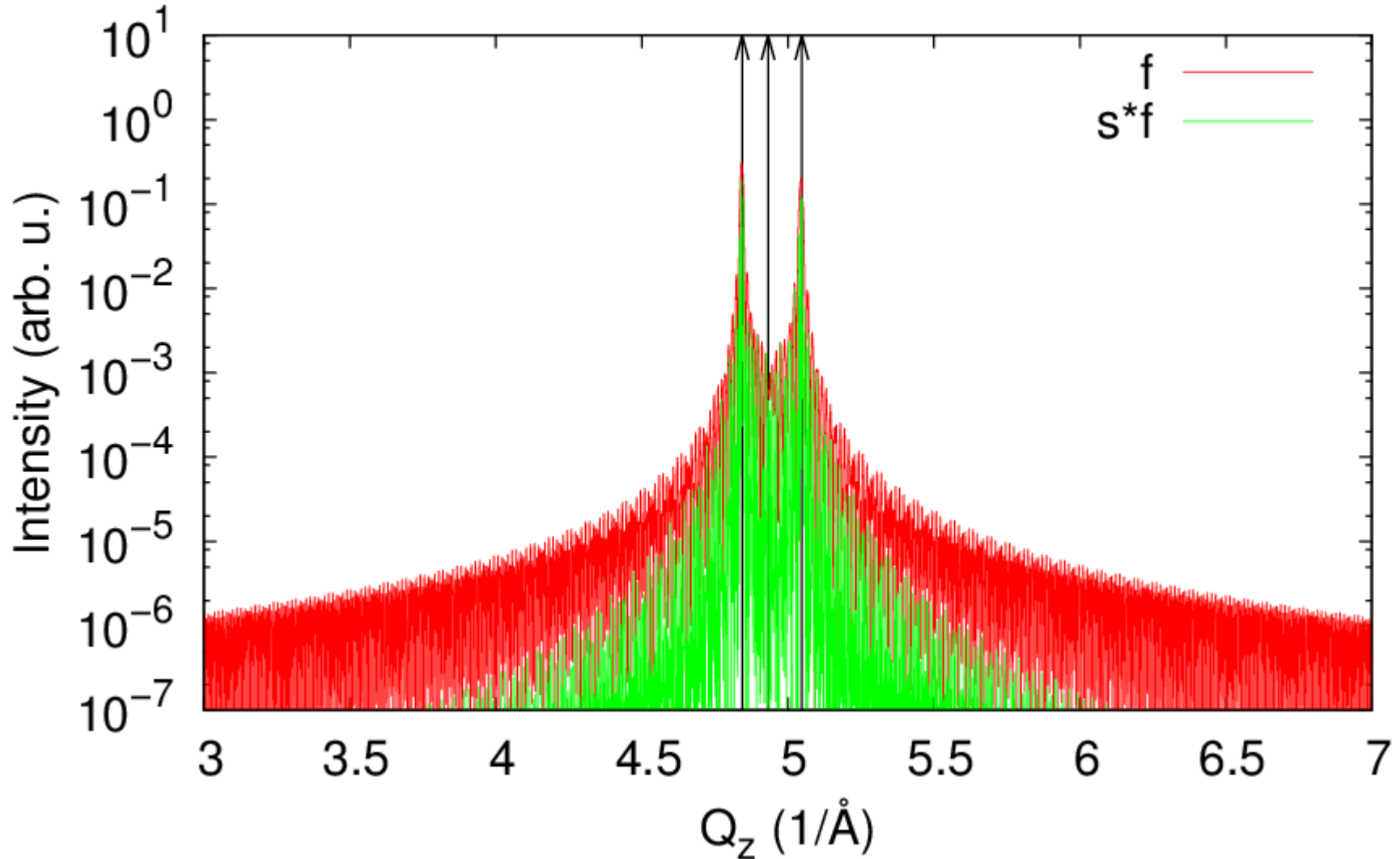
$$T_a=50\text{\AA}, T_b=150\text{\AA}, N=10, a_a=5.189\text{\AA}, a_b=4.979\text{\AA}$$



Epitaxní vrstvy

Multivrstva s – geometrický faktor, f – strukturní faktor, sf – celková intenzita

$$T_a=500\text{\AA}, T_b=400\text{\AA}, N=10, a_a=5.189\text{\AA}, a_b=4.979\text{\AA}$$



Epitaxní vrstvy

$$\chi^{\text{def}}(\mathbf{r}) = \sum_{\mathbf{g}} [\chi_{\mathbf{g}} + \delta\chi_{\mathbf{g}}(\mathbf{r})] e^{i\mathbf{g} \cdot (\mathbf{r} - \mathbf{u}(\mathbf{r}))} \equiv \sum_{\mathbf{g}} \chi_{\mathbf{g}}^{\text{def}}(\mathbf{r}) e^{i\mathbf{g} \cdot (\mathbf{r} - \mathbf{u}(\mathbf{r}))}$$

$$J_{\text{coh}}(\mathbf{Q}) = I_i \frac{K^6}{4} \left| \langle \chi_{\mathbf{h}}^{\text{def}} e^{-i\mathbf{h} \cdot \delta\mathbf{u}} \rangle \right|^2 \delta^{(2)}(\mathbf{Q}_{\parallel} - \mathbf{h}_{\parallel}^{\text{def}}) \times \\ \times \left| G_{\text{cryst}}(Q_z - h_z^{\text{def}}) \right|^2,$$

$$I_{\text{coh}} = I_i \frac{K^4}{4(K_{hz}^{\text{def}})^2} \left| \langle \chi_{\mathbf{h}}^{\text{def}} e^{-i\mathbf{h} \cdot \delta\mathbf{u}} \rangle \right|^2 \left| G_{\text{cryst}}(K_{hz}^{\text{def}} - \tilde{K}_{hz}^{\text{def}}) \right|^2$$

$$I_{\text{incoh}} = I_i \frac{K^4}{16\pi^2} \int \frac{d^2\mathbf{K}_{\parallel}}{K_z^2} \int d^2(\mathbf{r}_{\parallel} - \mathbf{r}'_{\parallel}) \int_{-T}^0 dz \times \\ \times \int_{-T}^0 dz' e^{-i(\mathbf{K} - \tilde{\mathbf{K}}_{\mathbf{h}}^{\text{def}}) \cdot (\mathbf{r} - \mathbf{r}')} M(\mathbf{r} - \mathbf{r}').$$

$$M(\mathbf{r}'' - \mathbf{r}''') = \text{Cov} \left(\chi_{\mathbf{h}}^{\text{def}}(\mathbf{r}'') e^{-i\mathbf{h} \cdot \delta\mathbf{u}(\mathbf{r}'')}, \chi_{\mathbf{h}}^{\text{def}}(\mathbf{r}''') e^{-i\mathbf{h} \cdot \delta\mathbf{u}(\mathbf{r}''')} \right)$$

$$\text{Cov}(a, b) = \langle ab^* \rangle - \langle a \rangle \langle b \rangle^*.$$

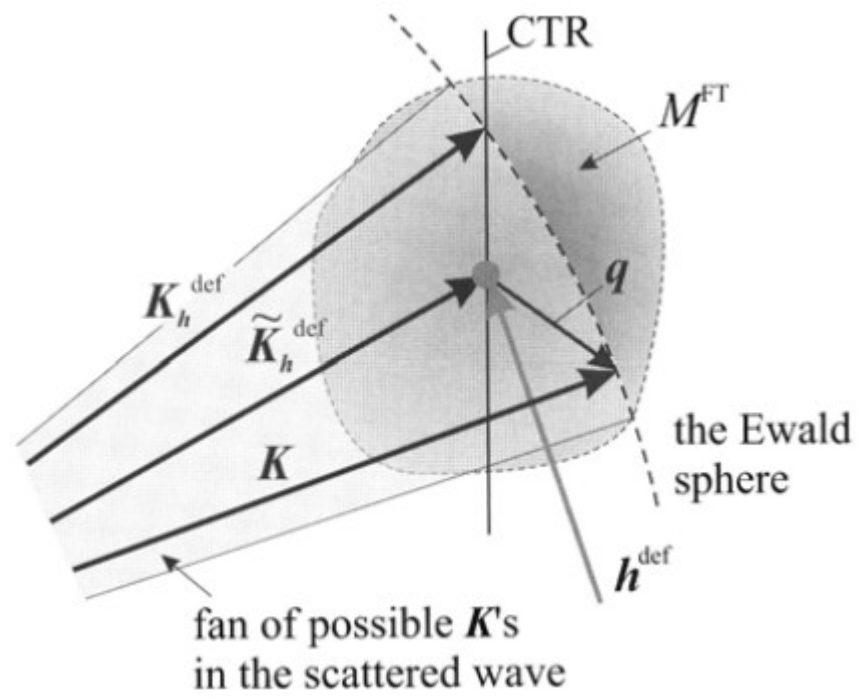
Epitaxní vrstvy

$$C(\mathbf{r}'', \mathbf{r}''') \equiv C(\mathbf{r}'' - \mathbf{r}''') = \\ = \left\langle \chi_{\mathbf{h}}^{\text{def}}(\mathbf{r}'') (\chi_{\mathbf{h}}^{\text{def}}(\mathbf{r}'''))^* e^{-i\mathbf{h} \cdot (\delta\mathbf{u}(\mathbf{r}'') - \delta\mathbf{u}(\mathbf{r}'''))} \right\rangle$$

correlation function of the crystal deformation

$$C(\mathbf{r}'' - \mathbf{r}''') = \left\langle \chi_{\mathbf{h}}^{\text{def}}(\mathbf{r}'') e^{-i\mathbf{h} \cdot \delta\mathbf{u}(\mathbf{r}'')} \right\rangle \left\langle \chi_{\mathbf{h}}^{\text{def}}(\mathbf{r}''') e^{-i\mathbf{h} \cdot \delta\mathbf{u}(\mathbf{r}''')} \right\rangle^* + \\ + M(\mathbf{r}'' - \mathbf{r}''').$$

Epitaxní vrstvy



Epitaxní vrstvy

$$\Psi^\alpha(\mathbf{r}) = \chi \mathbf{h} \left(1 - e^{-i\mathbf{h} \cdot \mathbf{v}^\alpha(\mathbf{r})} \right) + \Delta \chi \mathbf{h} \Omega^\alpha(\mathbf{r}) e^{-i\mathbf{h} \cdot \mathbf{v}^\alpha(\mathbf{r})}$$

$$M(\mathbf{r}, \mathbf{r}') = \int d^3 \mathbf{r}'' \sum_{\alpha} n^\alpha(\mathbf{r}'') \Psi^\alpha(\mathbf{r} - \mathbf{r}'') \Psi^{\alpha*}(\mathbf{r}' - \mathbf{r}'')$$

$$J_{\text{incoh}}(\mathbf{Q}) = I_i \frac{K^6 T}{16\pi^2} \sum_{\alpha} n^\alpha |\Psi^{\alpha\text{FT}}(\mathbf{q})|^2$$

$$\Psi_{\text{Huang}}^\alpha(\mathbf{r}) = \chi \mathbf{h} \left(1 - e^{-i\mathbf{h} \cdot \mathbf{v}^\alpha(\mathbf{r})} \right)$$

$$\Psi_{\text{Huang}}^\alpha(\mathbf{r}) \approx i\chi \mathbf{h} \cdot \mathbf{v}^\alpha(\mathbf{r}) \quad \mathbf{v}(\mathbf{r}) = \begin{cases} P\mathbf{r}/r^3 & \text{for } r > R \\ P\mathbf{r}/R^3 & \text{for } r \leq R \end{cases}$$

$$J_{\text{Huang}}(\mathbf{Q}) = I_i \frac{K^6 T}{16\pi^2} |\chi \mathbf{h}|^2 \sum_{\alpha} n^\alpha |\mathbf{h} \cdot \mathbf{v}^{\alpha\text{FT}}(\mathbf{q})|^2$$

Epitaxní vrstvy

$$\Psi_{\text{core}}^{\alpha}(\mathbf{r}) = \Delta\chi_h \Omega^{\alpha}(\mathbf{r}) e^{-i\mathbf{h}\cdot\mathbf{v}^{\alpha}(\mathbf{r})}$$

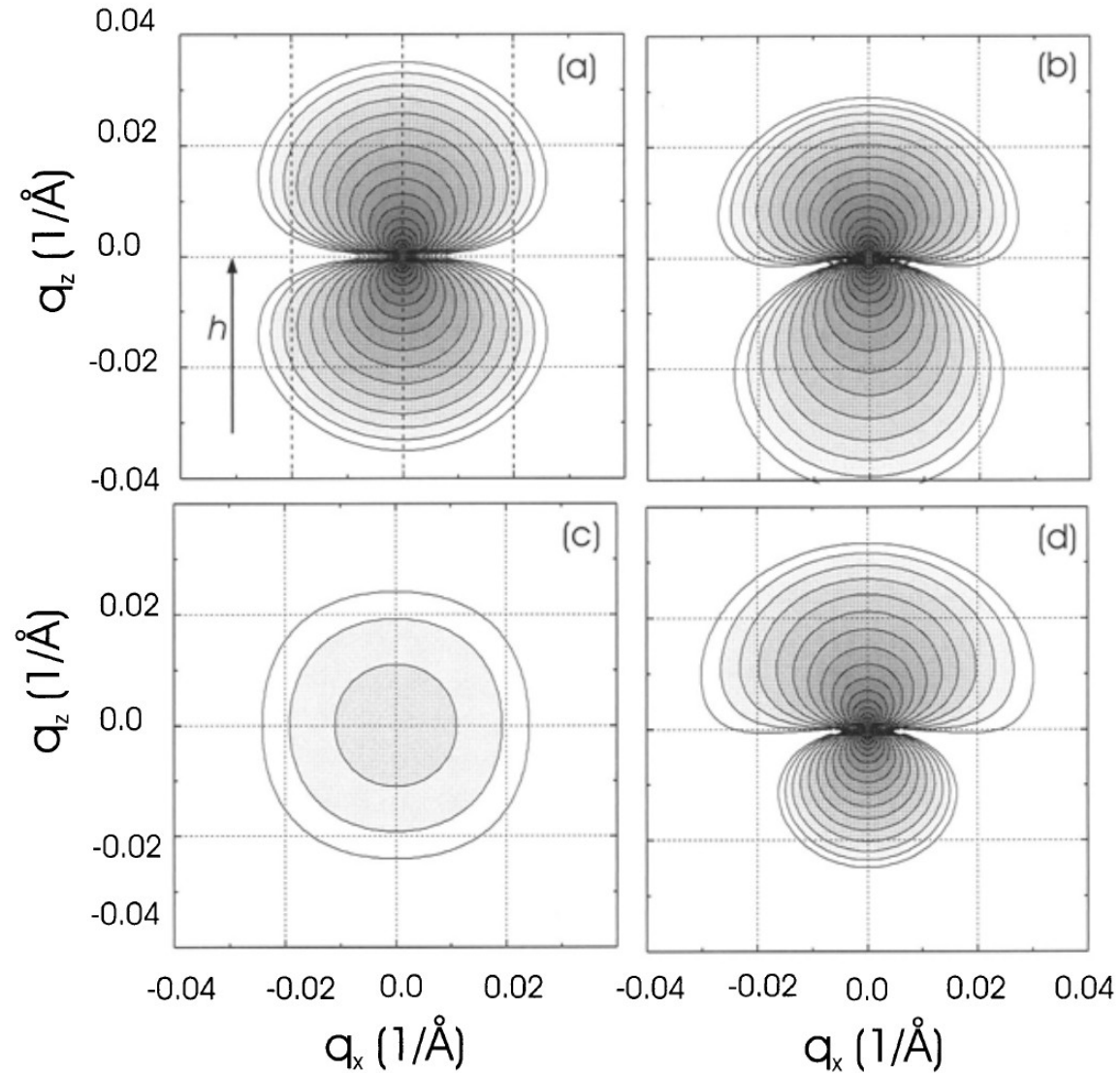
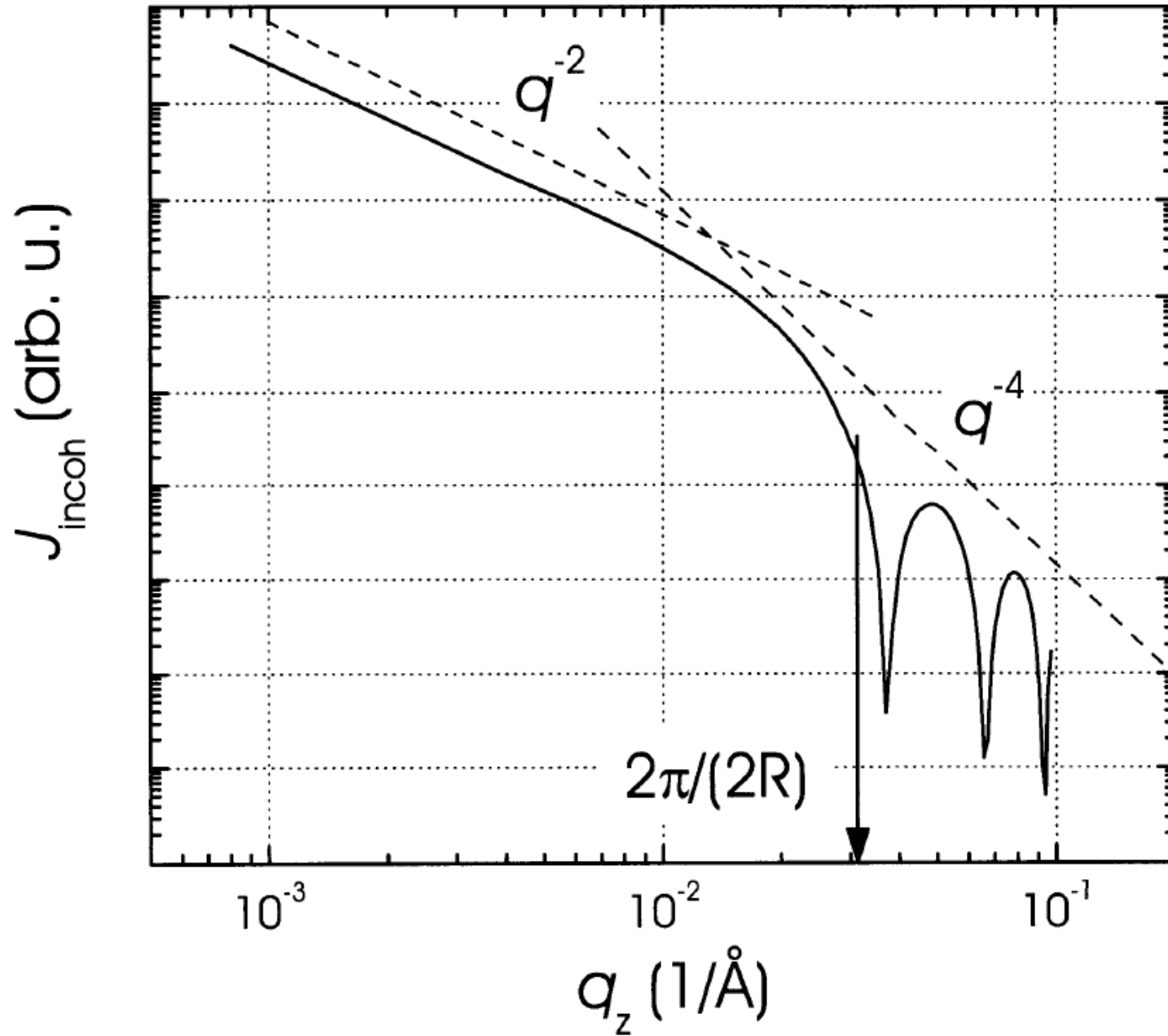


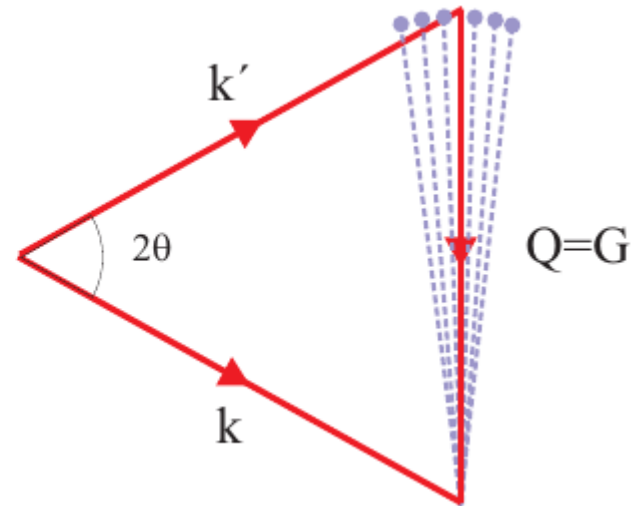
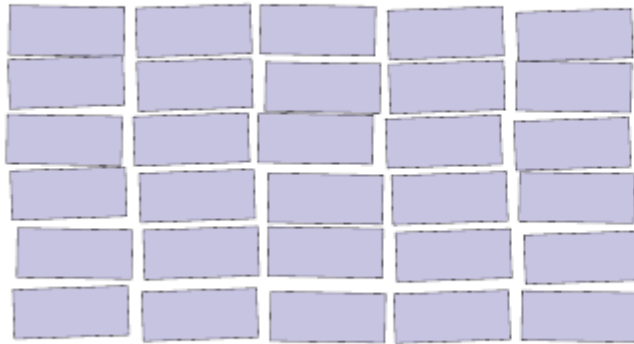
Fig. 10.1. Diffuse intensity distribution in reciprocal space calculated for spherical inclusions with radius 10 nm and the lattice mismatch 0.5%. Panel (a) shows the Huang scattering using the approximation $\exp(-i\mathbf{h}\cdot\mathbf{v}) - 1 \approx -i\mathbf{h}\cdot\mathbf{v}$; in (b) the Huang scattering is presented without this approximation. Panel (c) represents the core scattering; in (d) the total scattered intensity is depicted. The contour step is $10^{0.25}$.

Epitaxní vrstvy



Epitaxní vrstvy

Mosaic blocks of small perfect crystals



Epitaxní vrstvy

$$C(\mathbf{r} - \mathbf{r}') = |\chi_{\mathbf{h}}|^2 \left\langle e^{-i\mathbf{h} \cdot (\mathbf{u}(\mathbf{r}) - \mathbf{u}(\mathbf{r}'))} \right\rangle = \\ = |\chi_{\mathbf{h}}|^2 P(\mathbf{r} - \mathbf{r}') \left\langle e^{-i\mathbf{h} \cdot (\mathbf{u}(\mathbf{r}) - \mathbf{u}(\mathbf{r}'))} \right\rangle_{\text{rot}},$$

$$P(\boldsymbol{\rho}) = \frac{\int d^3\mathbf{r}'' \Omega(\mathbf{r}'') \Omega(\boldsymbol{\rho} + \mathbf{r}'')}{\int d^3\mathbf{r}'' \Omega(\mathbf{r}'')}, \quad \boldsymbol{\rho} = \mathbf{r} - \mathbf{r}'.$$

$$P(\boldsymbol{\rho}) = \begin{cases} 1 - \frac{3}{4} \frac{|\boldsymbol{\rho}|}{R} + \frac{1}{16} \left(\frac{|\boldsymbol{\rho}|}{R} \right)^3 & \text{for } |\boldsymbol{\rho}| \leq 2R \\ 0 & \text{for } |\boldsymbol{\rho}| > 2R \end{cases}$$

$$\left\langle e^{-i\mathbf{h} \cdot (\mathbf{u}(\mathbf{r}) - \mathbf{u}(\mathbf{r}'))} \right\rangle_{\text{rot}} = \exp \left[-\frac{1}{6} \Delta^2 |\mathbf{h} \times (\mathbf{r} - \mathbf{r}')|^2 \right]$$

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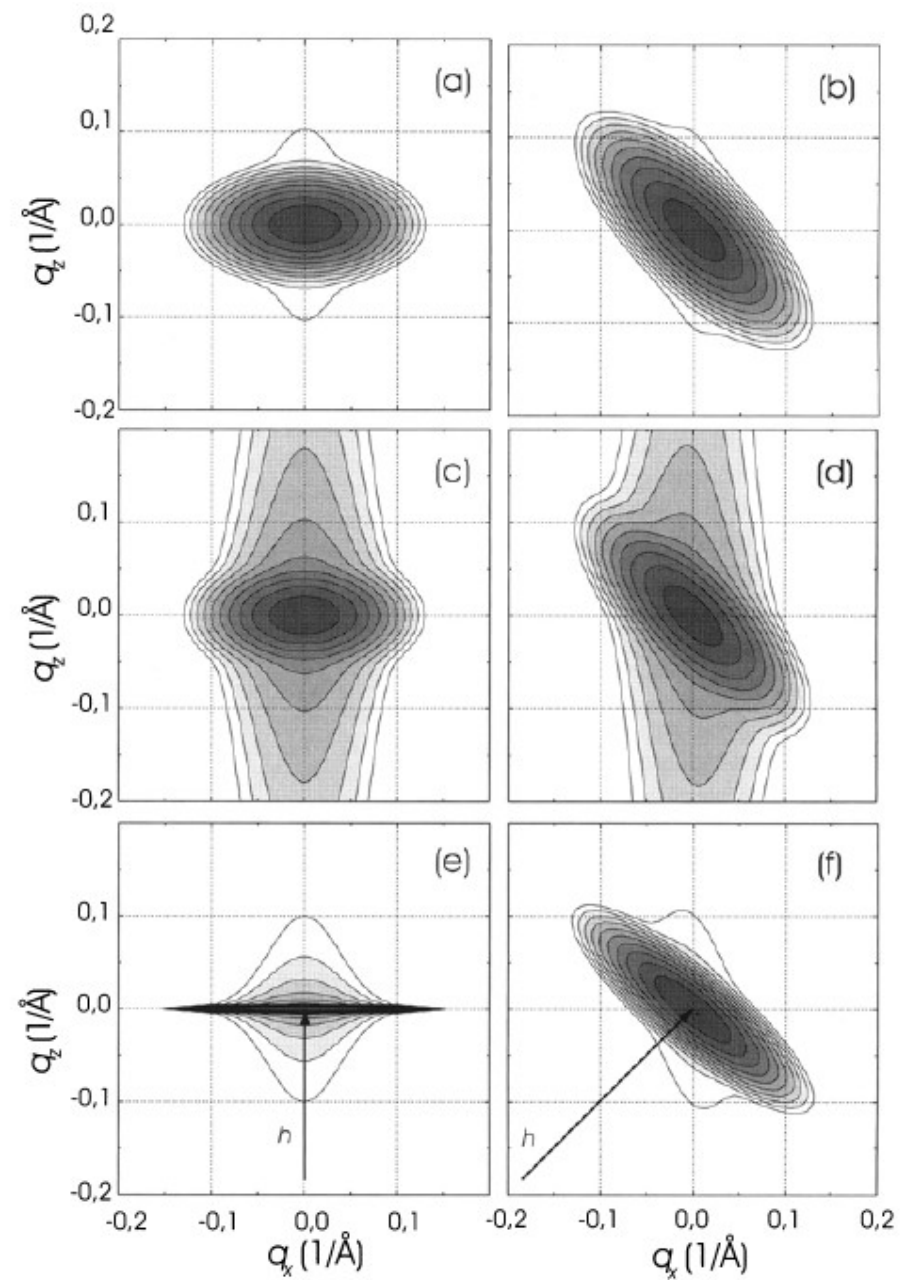


Fig. 10.15. The intensity maps of a mosaic layer calculated in symmetric 004 diffraction (a,c,e) and asymmetric 404 diffraction (b,d,f). The layer thickness was $10 \mu\text{m}$ (a,b,e,f) and 100 nm (c,d). In all panels, the root mean square misorientation of the blocks was 0.5° . In (a-d) the blocks were spherical with radius 10 nm ; in (e,f) they were columnar with the horizontal radius 10 nm and height $2 \mu\text{m}$. In (e) and (f) the directions of the diffraction vectors are denoted by arrows; the step of the intensity contours was $\sqrt{10}$.